

Kvadrupólová hmotnostní spektrometrie reaktivního plazmatu

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Thanks to: **Simon Schneider**
 Simon Große-Kreul
 Dirk Ellerweg
 Simon Hübner
 Achim von Keudell

Motivation: analysis of the plasma

Example of CCP or ICP plasmas

Stable species x highly reactive species x ions

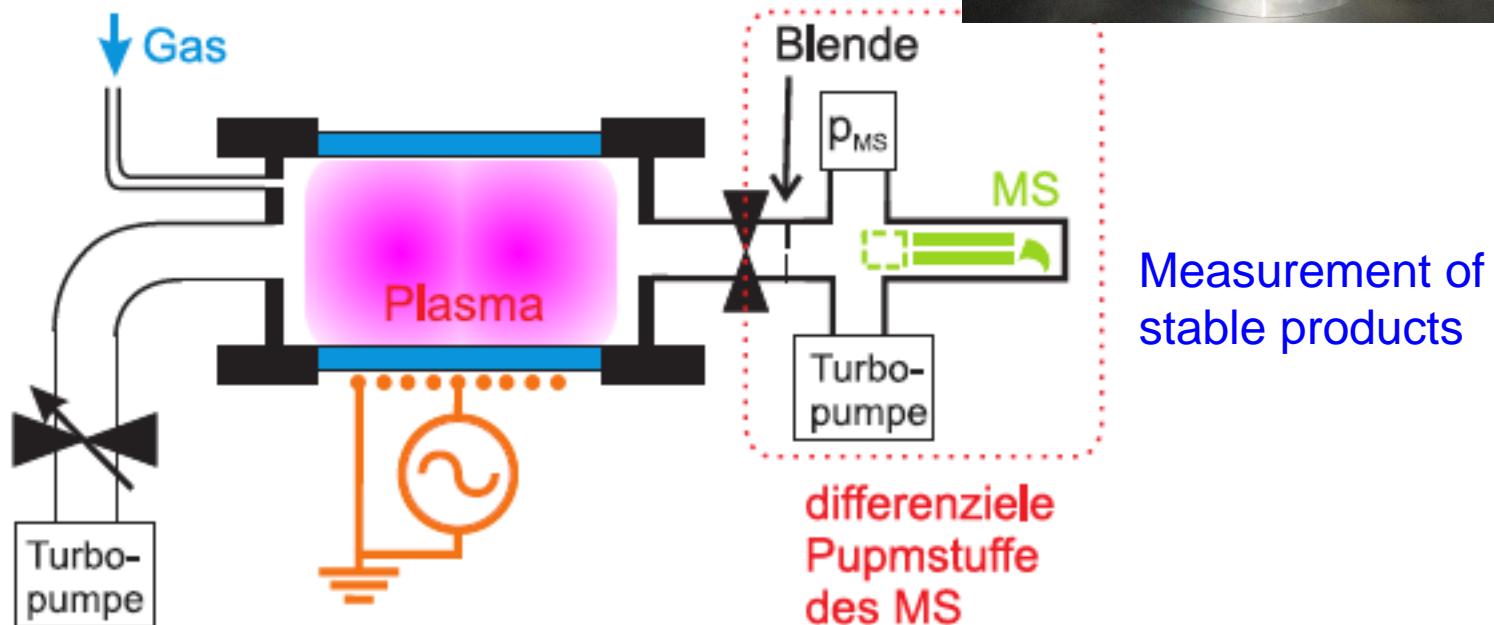
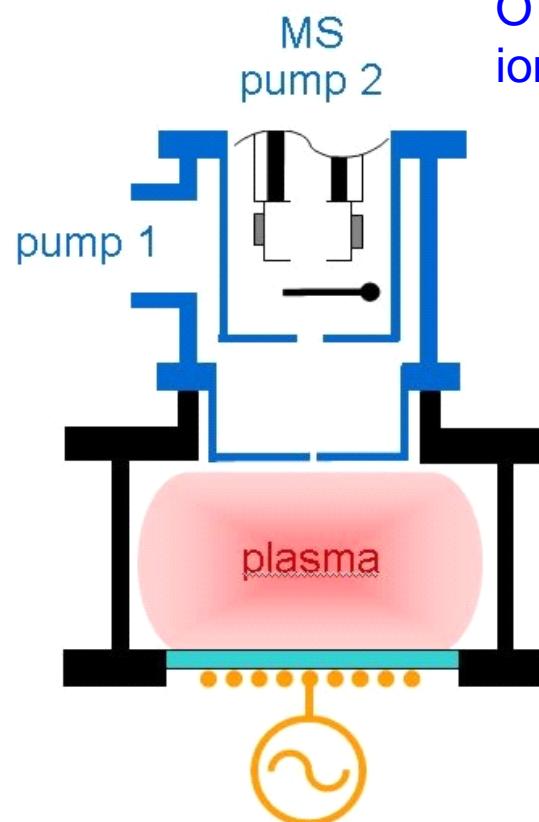
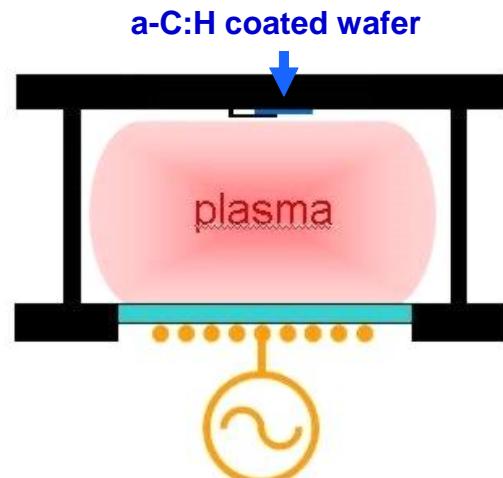
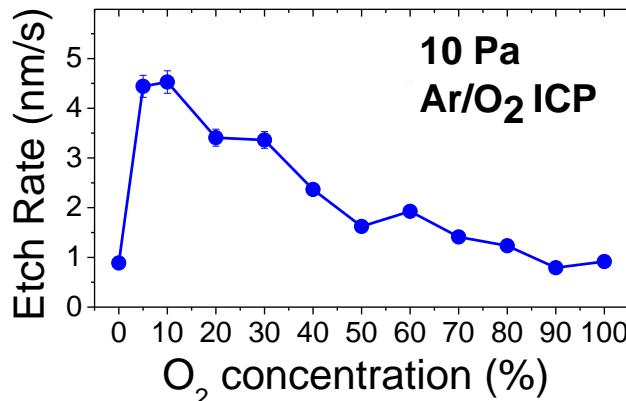


Abbildung 3.1: Skizze des Versuchsaufbaus. (entnommen aus [10])

Motivation: analysis of the plasma

Example of CCP or ICP plasmas

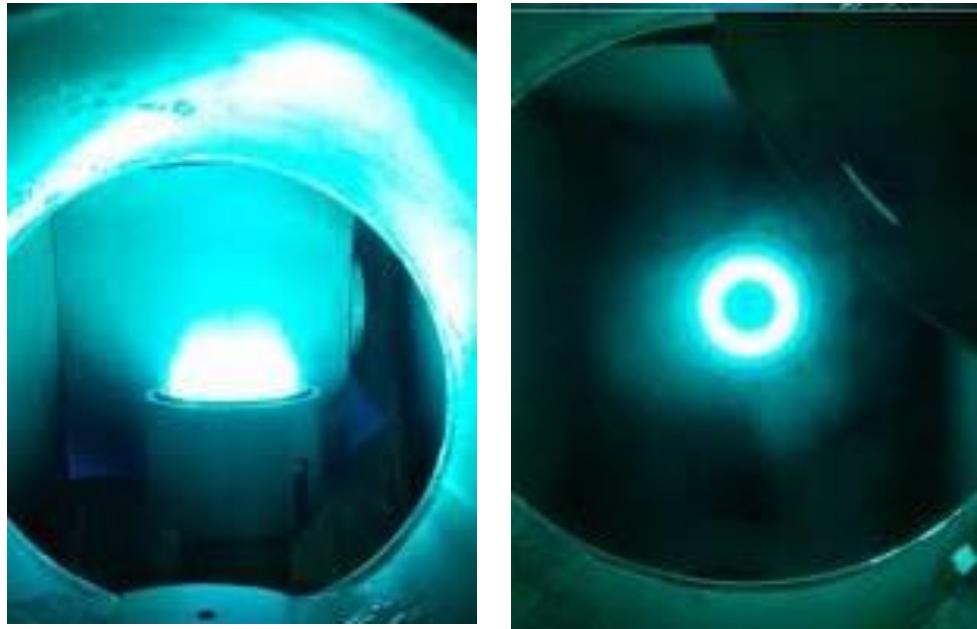
Stable species x highly reactive species x ions



Motivation: analysis of the HiPIMS plasmas

Example of HiPIMS discharges

- highly transient plasma
- mainly reactive short-lived species



Even stable species (such as Ar or O₂) have a spatial density profile

Ionization zones (“spokes”)

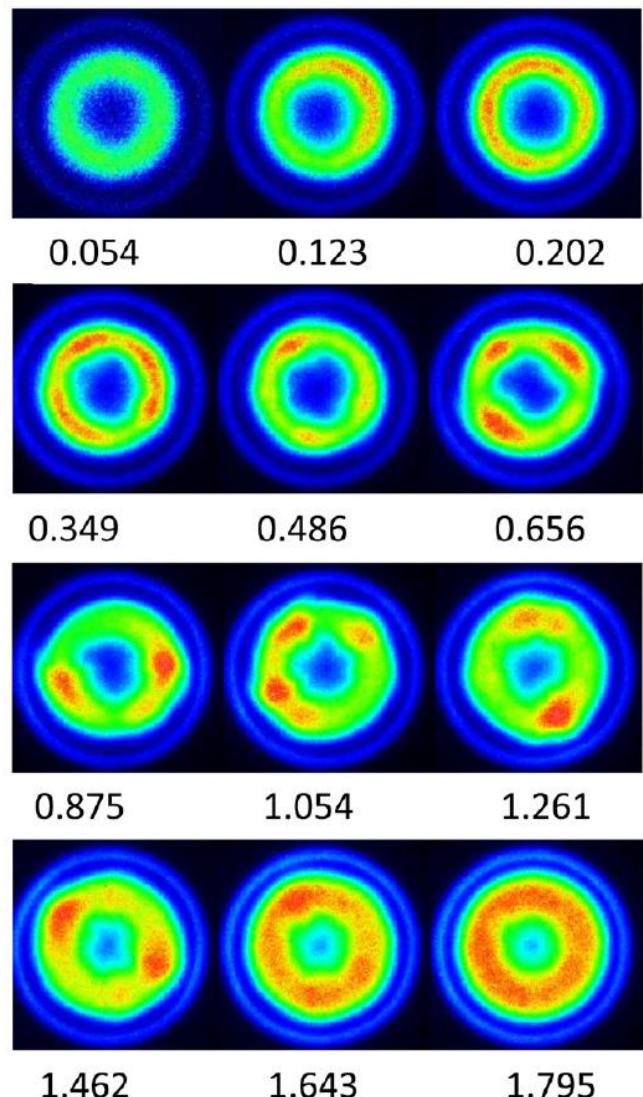
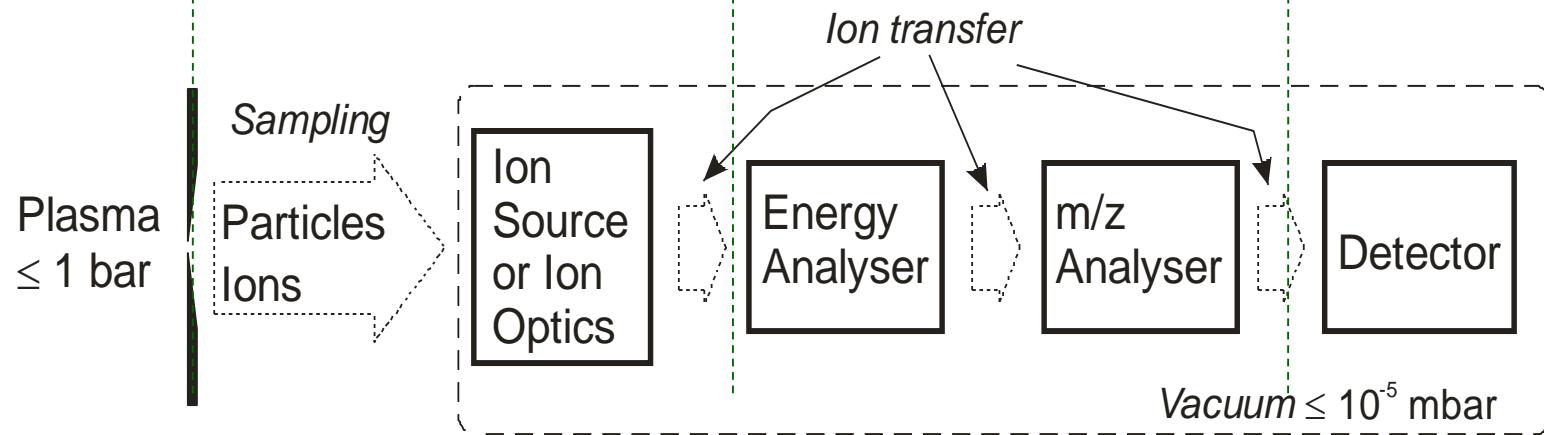


Figure 2. ICCD images of a chromium target at different power densities in kW cm⁻² as indicated. The images are taken at 180 μ s of 200 μ s pulses and Ar at 0.26 Pa.

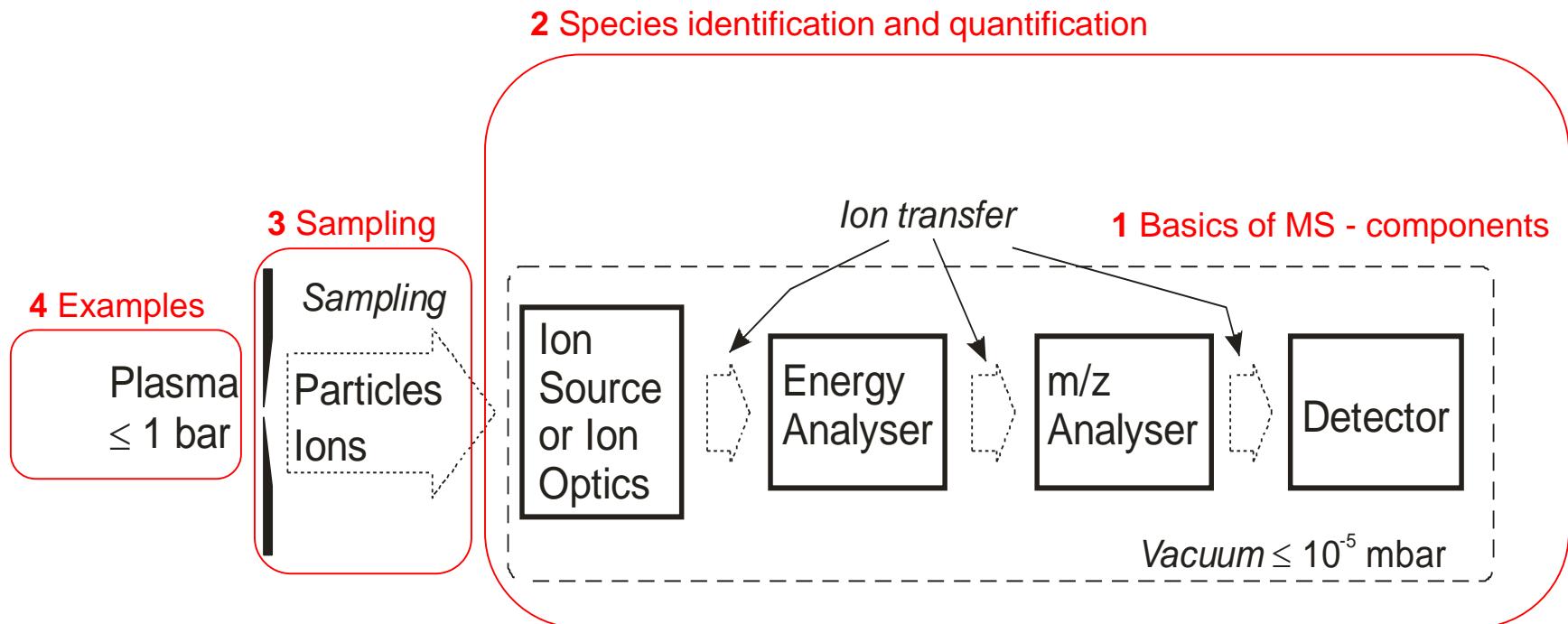
Motivation: Analysis of unknown analyte



Mass spectrometry in general



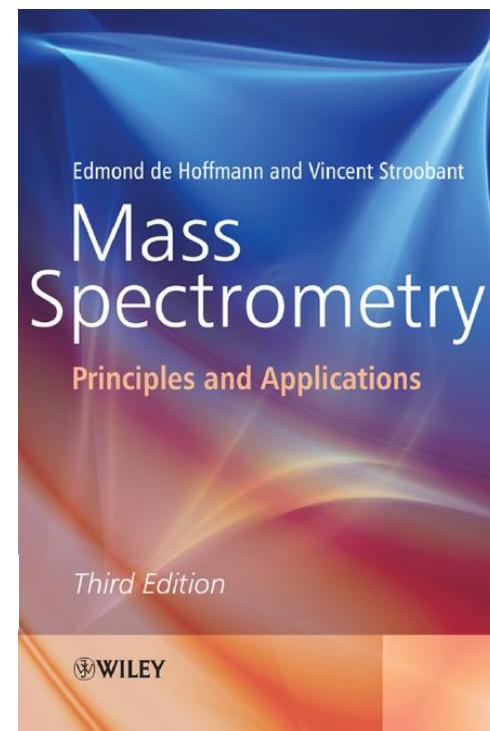
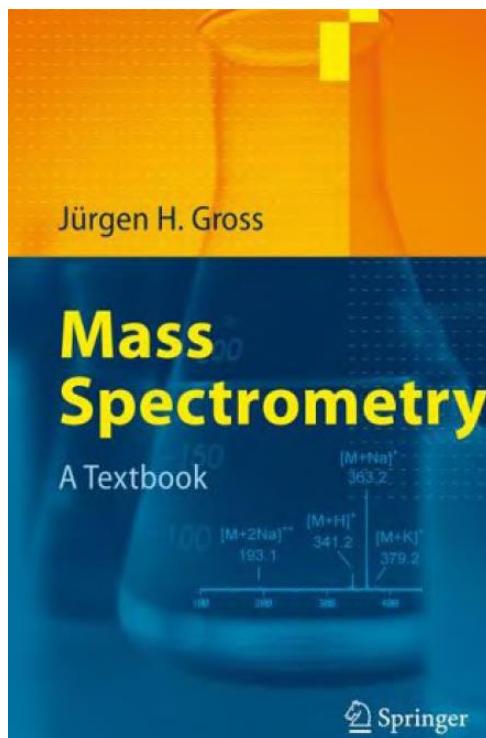
Outline



Literature

J. Phys. D: Appl. Phys. 45 (2012) 403001 (23pp)

TOPICAL REVIEW



Quadrupole mass spectrometry of reactive plasmas

J Benedikt, A Hecimovic, D Ellerweg and A von Keudell

Plasma Sources Sci. Technol. 24 (2015) 044008 (15pp)

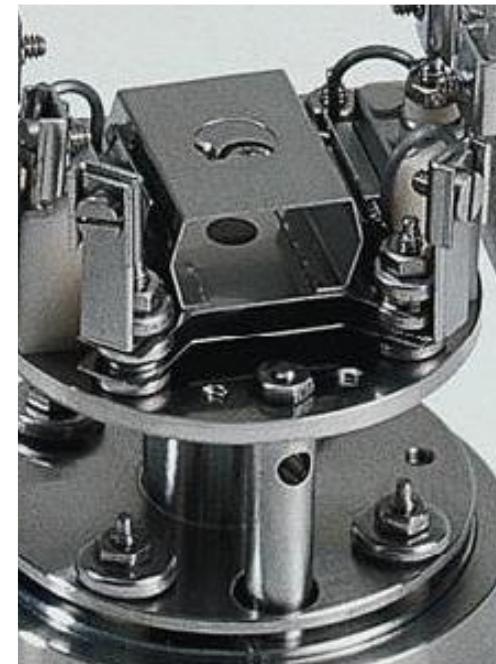
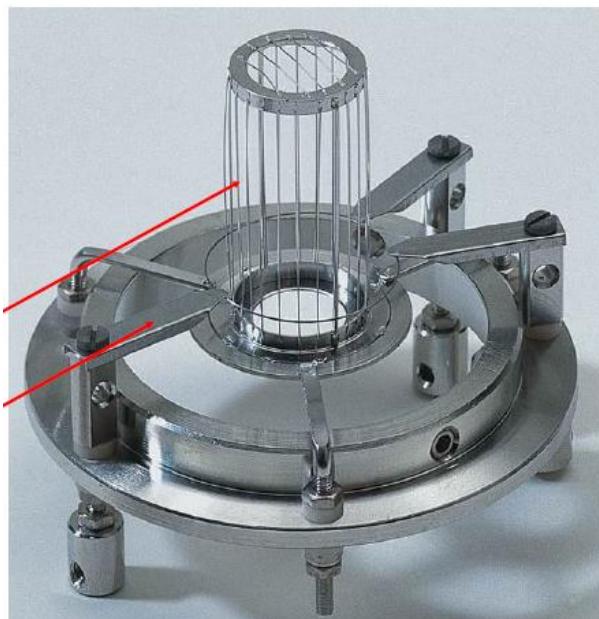
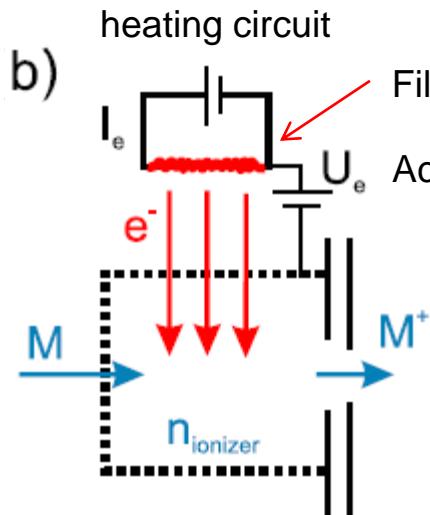
[doi:10.1088/0963-0252/24/4/044008](https://doi.org/10.1088/0963-0252/24/4/044008)

Mass spectrometry of atmospheric pressure plasmas

S Große-Kreul¹, S Hübner¹, S. Schneider¹, D Ellerweg¹, A von Keudell¹,
S Matejčík² and J Benedikt¹

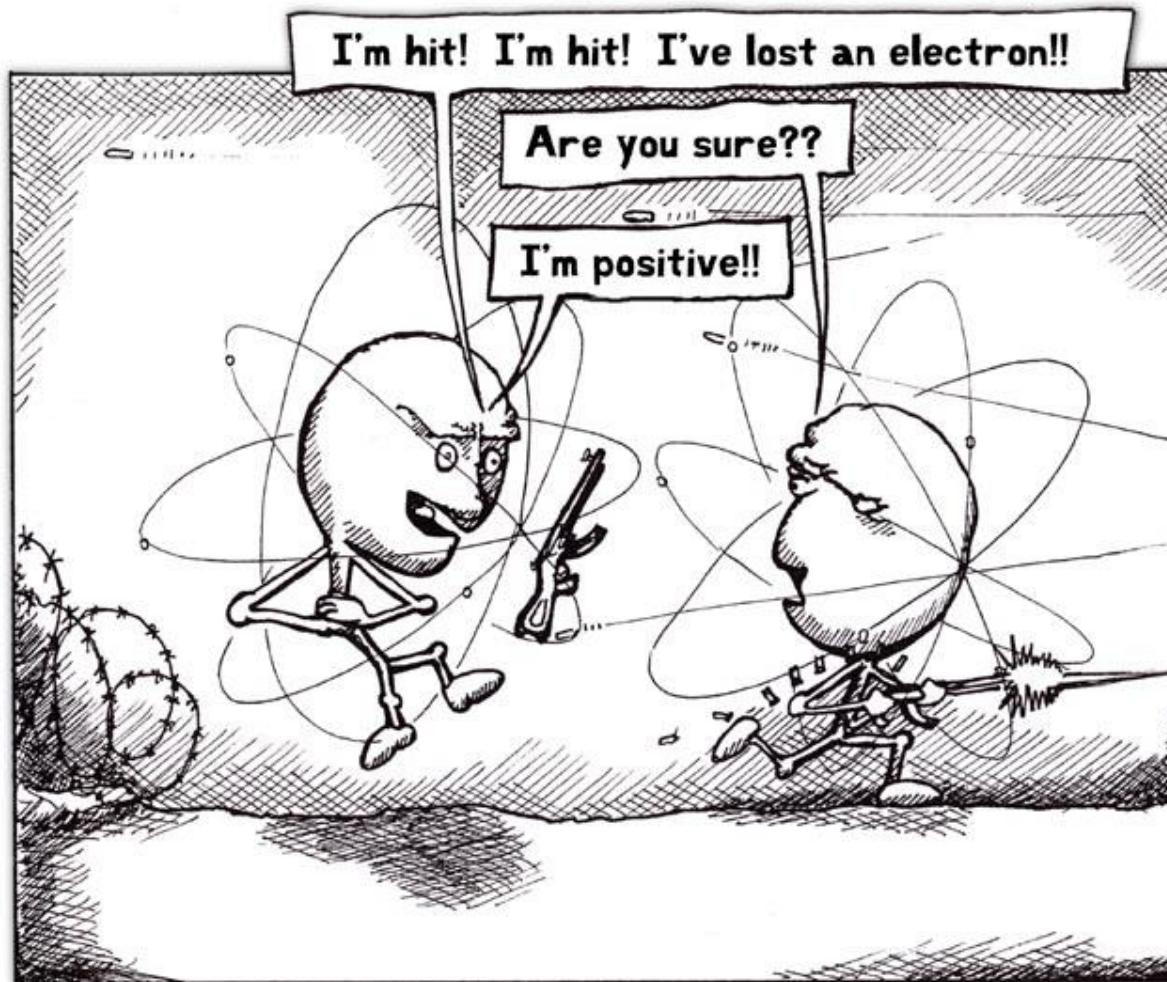
MS components: electron impact ionizer

Electron source: heated filament



 INFICON
distributed by
 PFEIFFER VACUUM

MS components: electron impact ionizer



Another casualty in the War of the Atoms

MS components: Quadrupole Mass Filter

Combined RF and DC electric fields for mass analysis

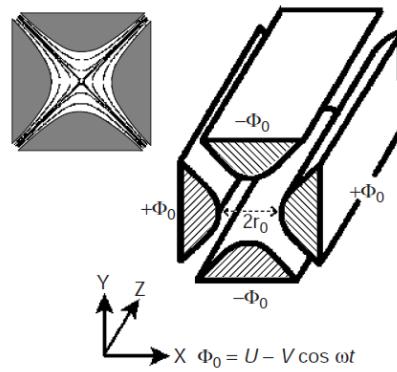
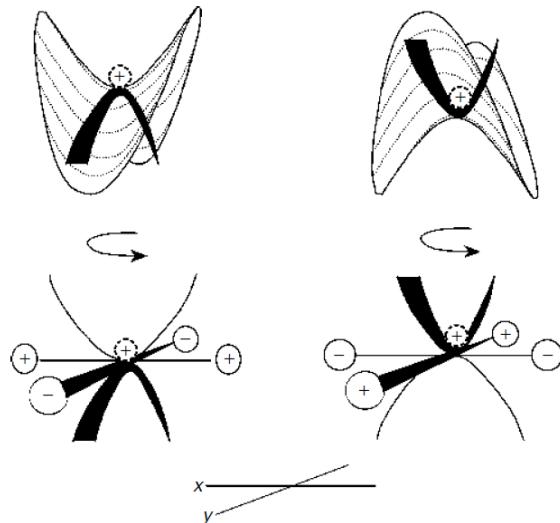
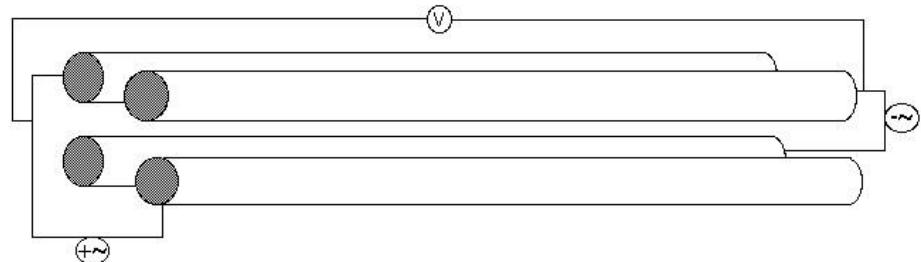


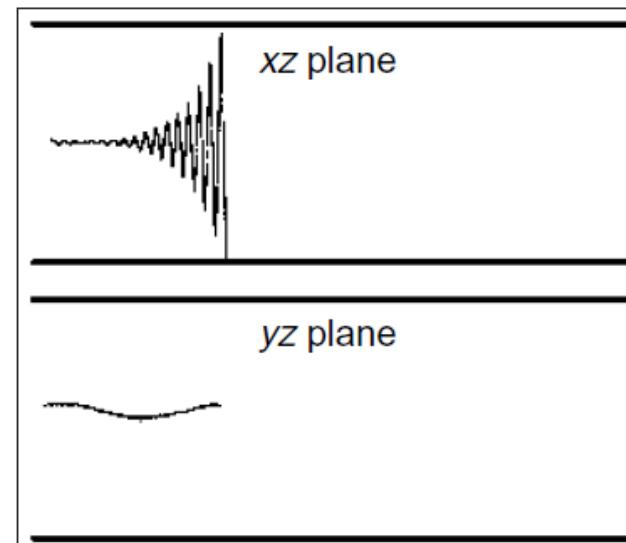
Figure 2.5
Quadrupole with hyperbolic rods and applied potentials. The equipotential lines are represented above, on the left.



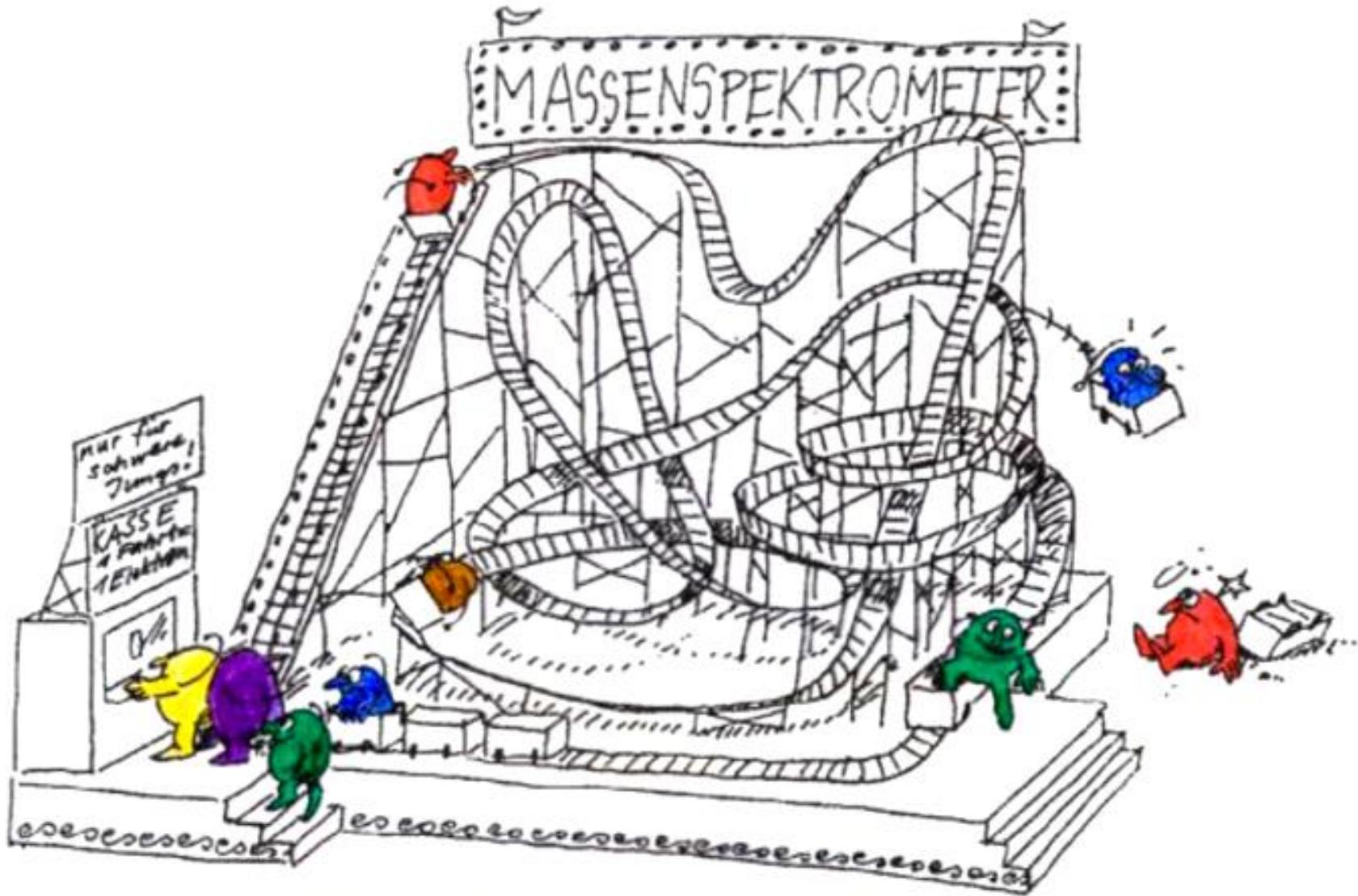
Quadrupole Mass Filter



Ion trajectories



Stable along y , unstable along x



FÄLSCHE SELBSTEINSCHÄZUNG HAT SCHON MANCHES ATOMI
AUS DER BAHN GEWORFEN.

MS components: Detectors

Secondary electron multipliers (SEM)

With discrete dynodes

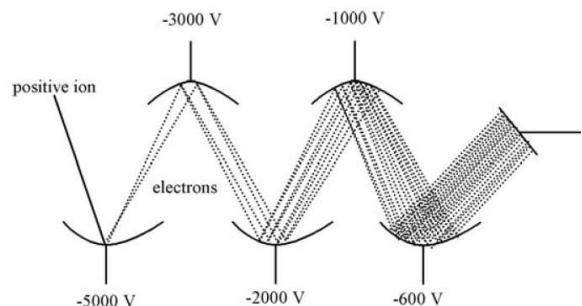
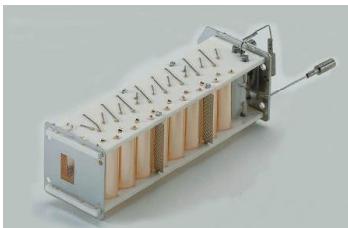
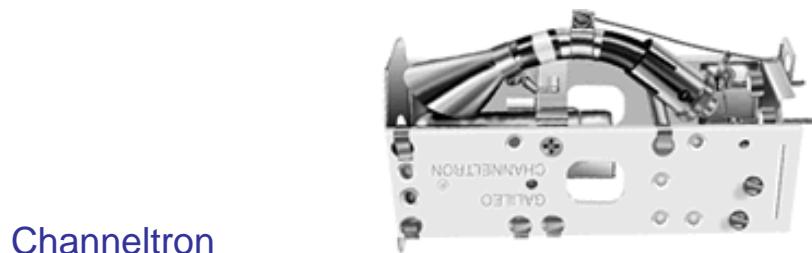


Figure 3.2
Schematic diagram of electron multiplier. The first dynode is a conversion dynode to convert ions into electrons.



Channeltron

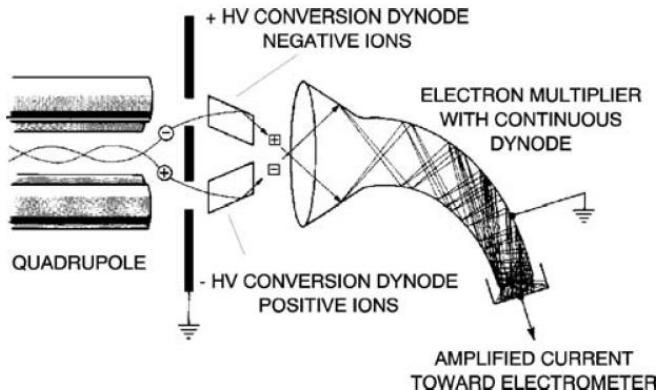
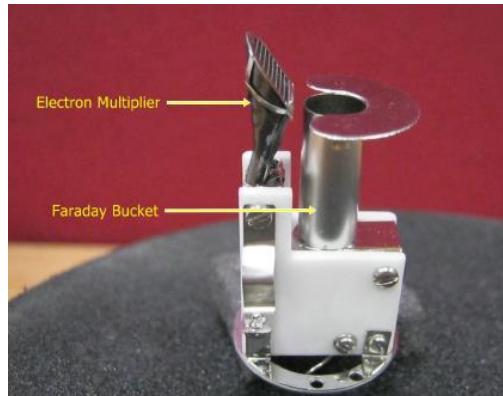
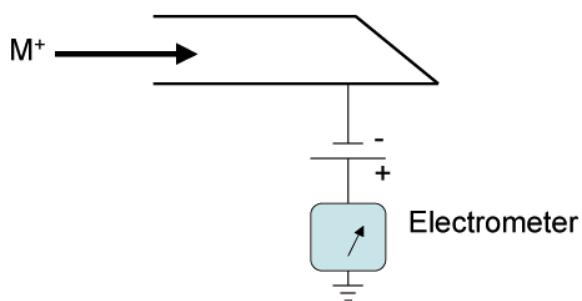


Figure 3.3
Continuous dynode electron multiplier, also known as the channeltron. \circ , incident ions; \square , secondary particles. Reproduced (modified) from Finnigan MAT documentation, with permission.

Faraday cup



MS components: Detectors

A typical operating curve for the detector is shown in Figure 3.1.

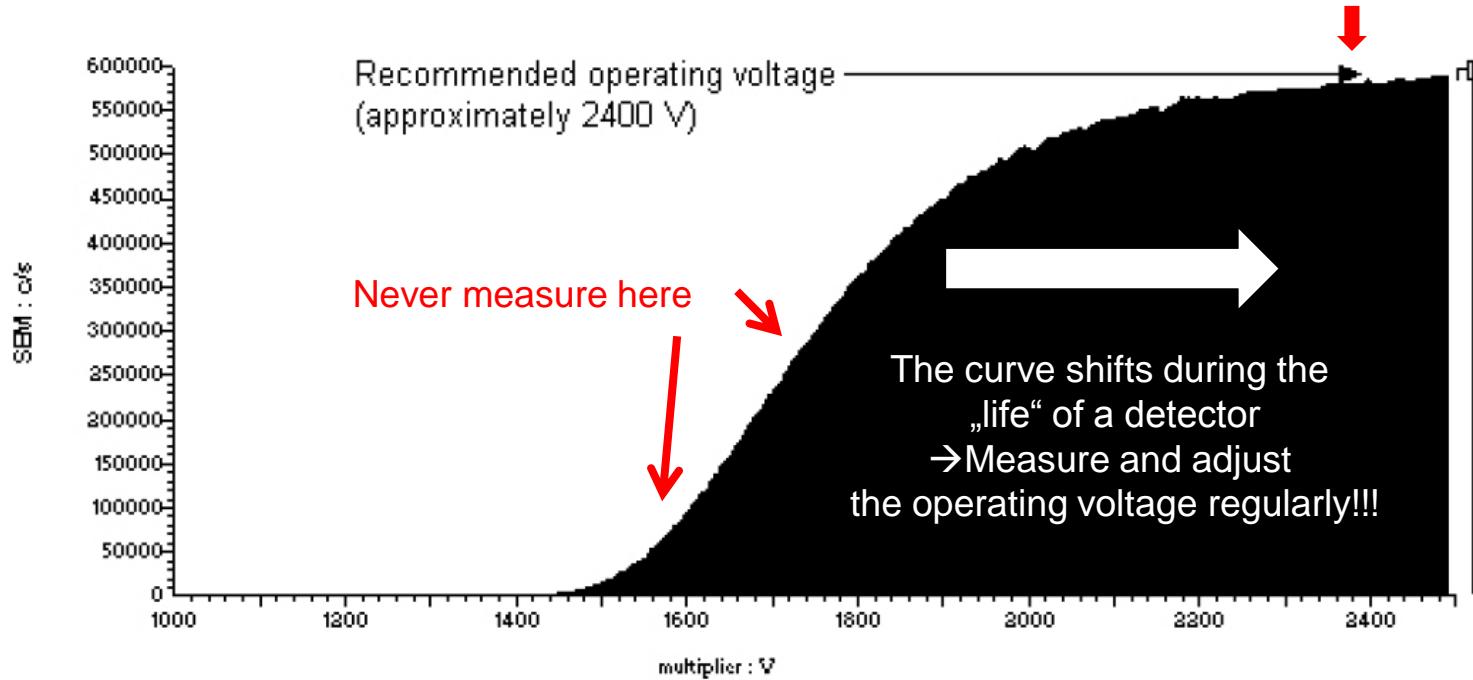


Figure 3.1 Typical detector operating curve

Detector is a „consumable“ – has a limited lifetime depending on overall number of counts measured!!!

Typical lifetime ~ 1-5 years

MS components: Detectors

Remark: The Use of Channeltron® Detectors

The Channeltron® Electron Multiplier has a history of dependability in mass spectrometer applications. The following instructions and precautions are presented here in order that the user can achieve the maximum useful lifetime of a Channeltron detector.

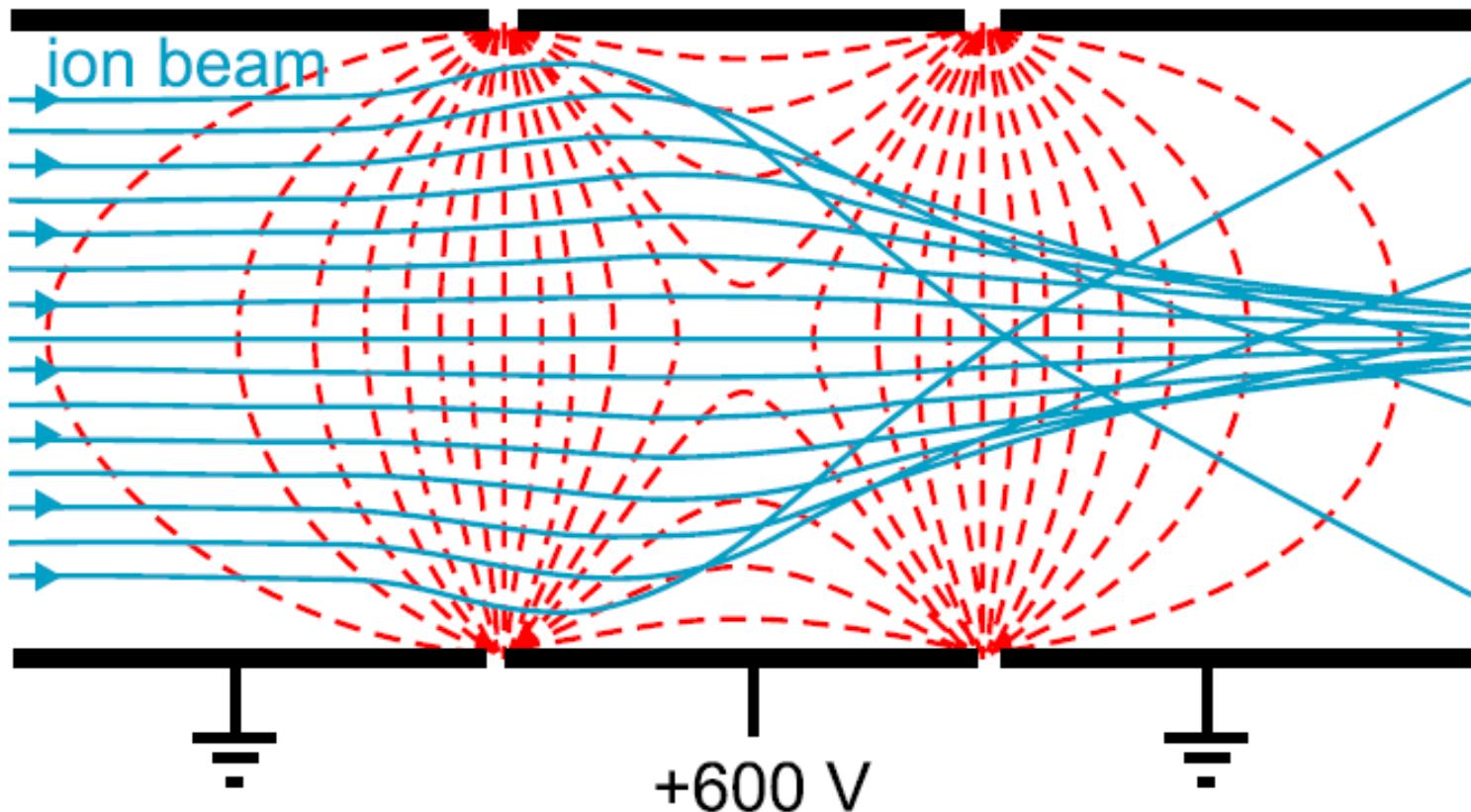
1. Mounting work should be done in clean vacuum fashion, i.e., the detector should be handled with talc free finger cots or lint free gloves. Care should be taken to avoid dust, lint, or other particulate matter. Nothing should touch the active areas of the detector.
2. Channeltrons are normally operated at pressures of 10^{-5} or lower. Higher pressure operation is observed to increase the background current and can result in shortened life. **Do not apply high voltage at pressures greater than 10^{-4} torr as arcing can occur and permanent destruction of the Channeltron surface is possible.**
3. Channeltrons are customarily operated at 1500 to 3000 volts. The maximum rated voltage difference between input and output leads is 3000 volts. Care should be taken to operate at a voltage which gives sufficient gain to achieve acceptable results. **Higher gains will shorten Channeltron lifetimes in inverse proportion, i.e. 2x the gain results in 1/2 the potential lifetime.**
4. During the first few days of operation of a new detector, it is recommended that high output currents be avoided (i.e. inputs above 10^{-9} amps while operating at gains in excess of 10^7). Taking this initial burn-in precaution can prevent premature failure.
5. Backstreaming from oil diffusion pumps or roughing pumps should not be permitted. It is recommended that cold traps and molecular sieve traps be operated and maintained to manufacturers specifications.

Warranty - All multipliers come with a **one year prorated warranty starting at the date of shipment**. Multipliers with insufficient gain or excessive noise should be returned to S.I.S. for evaluation and testing. If the multiplier proves to be defective due to manufacturing defects it will be replaced at no charge during the first three months of use and prorated thereafter based on a one year life and a gain of 1×10^5 at 3 KV. Multipliers which test properly or which were damaged due to operator fault or carelessness will not be replaced, and user will be billed --- for testing. Channeltron® is a registered trademark of Burle Electro Optics Corp.

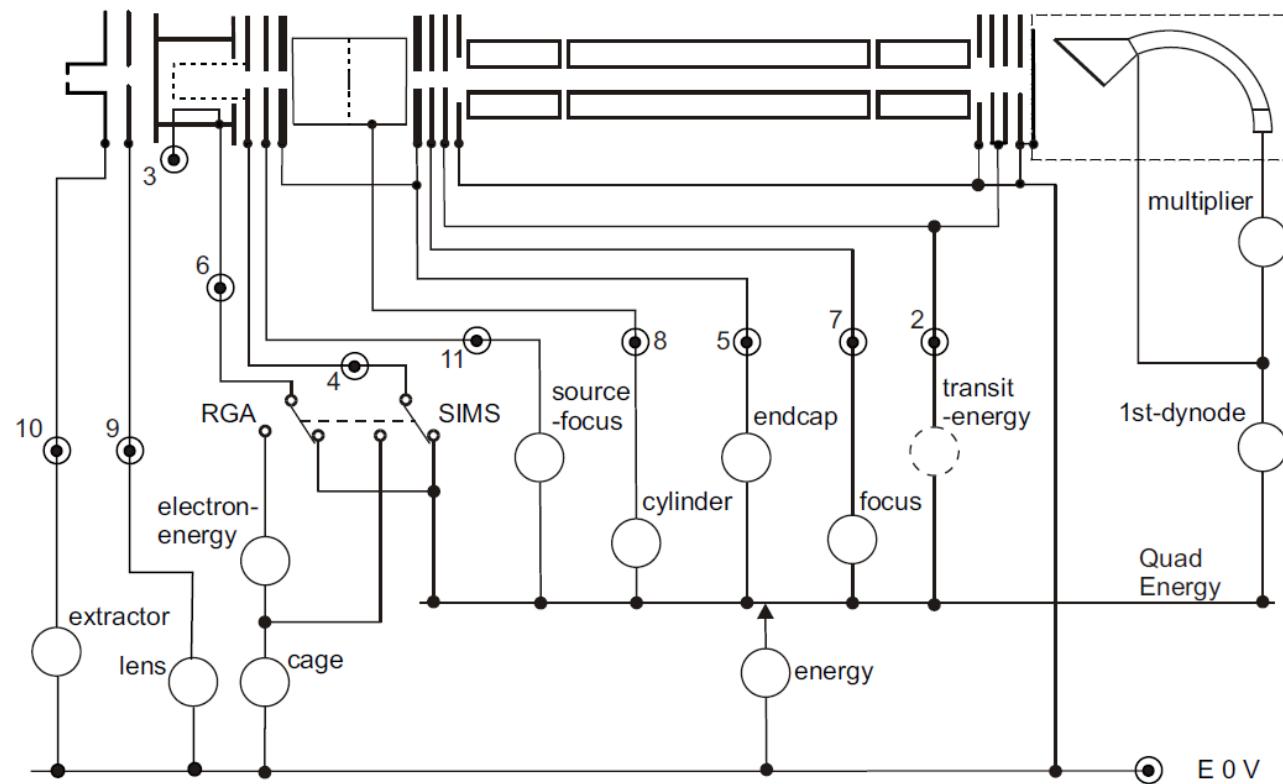
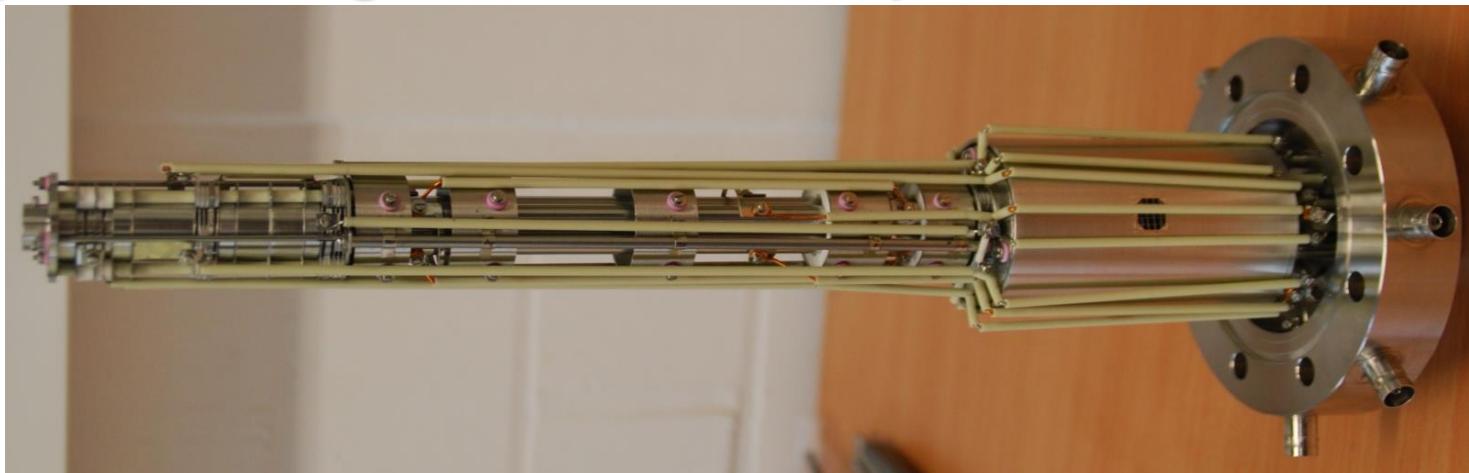
MS components: single ion lens

Used to guide and focus the ions in the MS

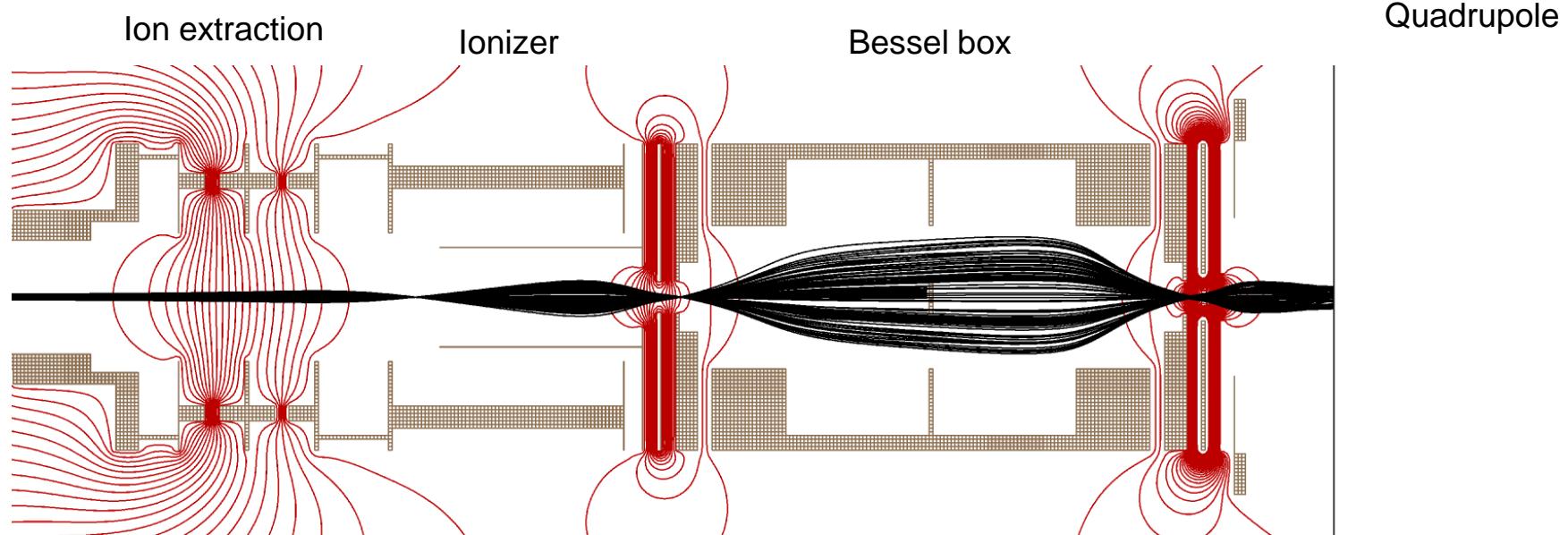
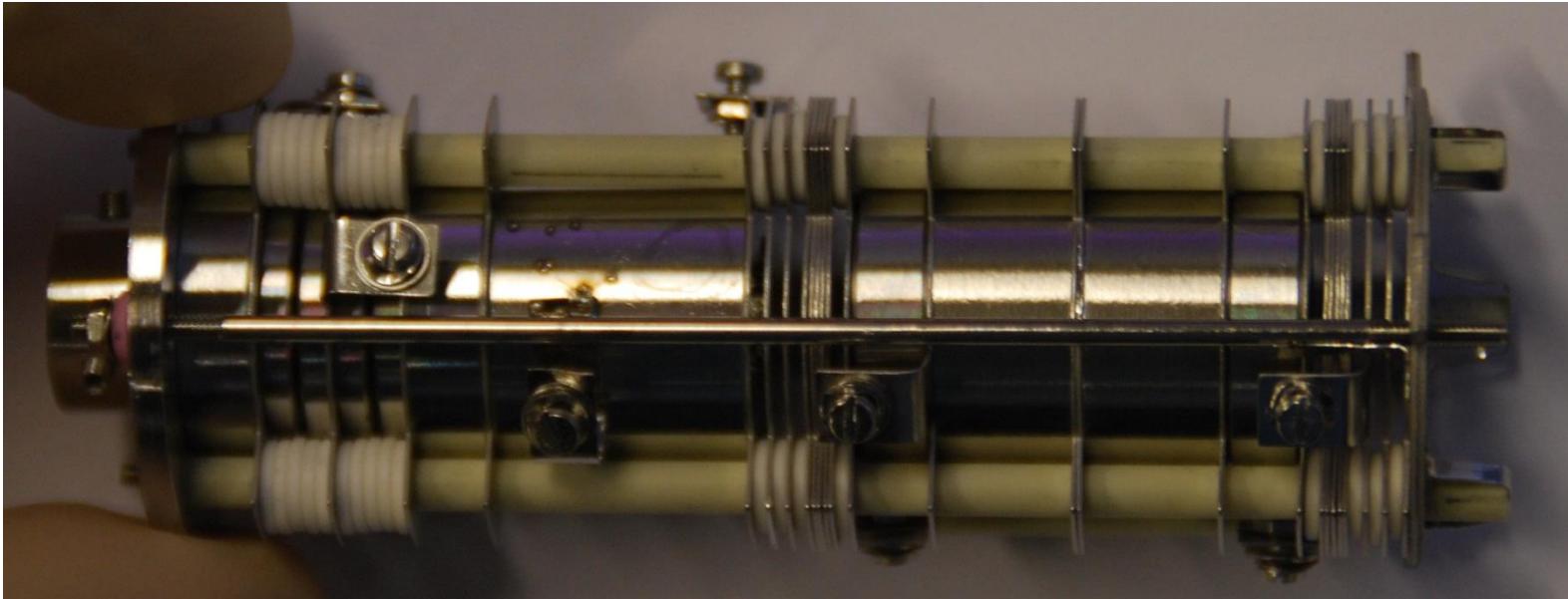
ring electrodes



All components together: for example HIDEN PSM



MS components: combination of ion lenses



Simulation: Simion 8.1 SW

MS components: energy filters

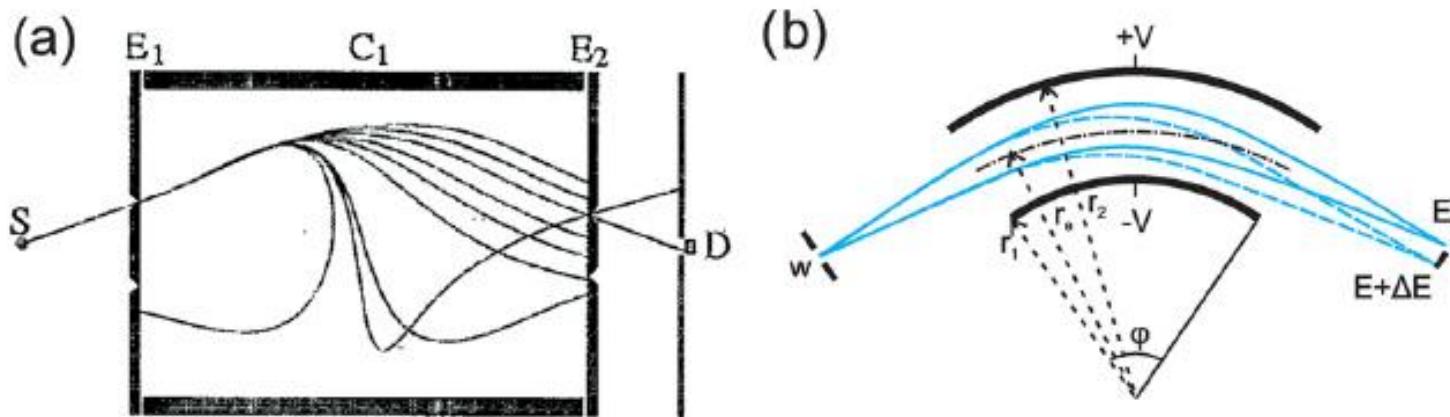
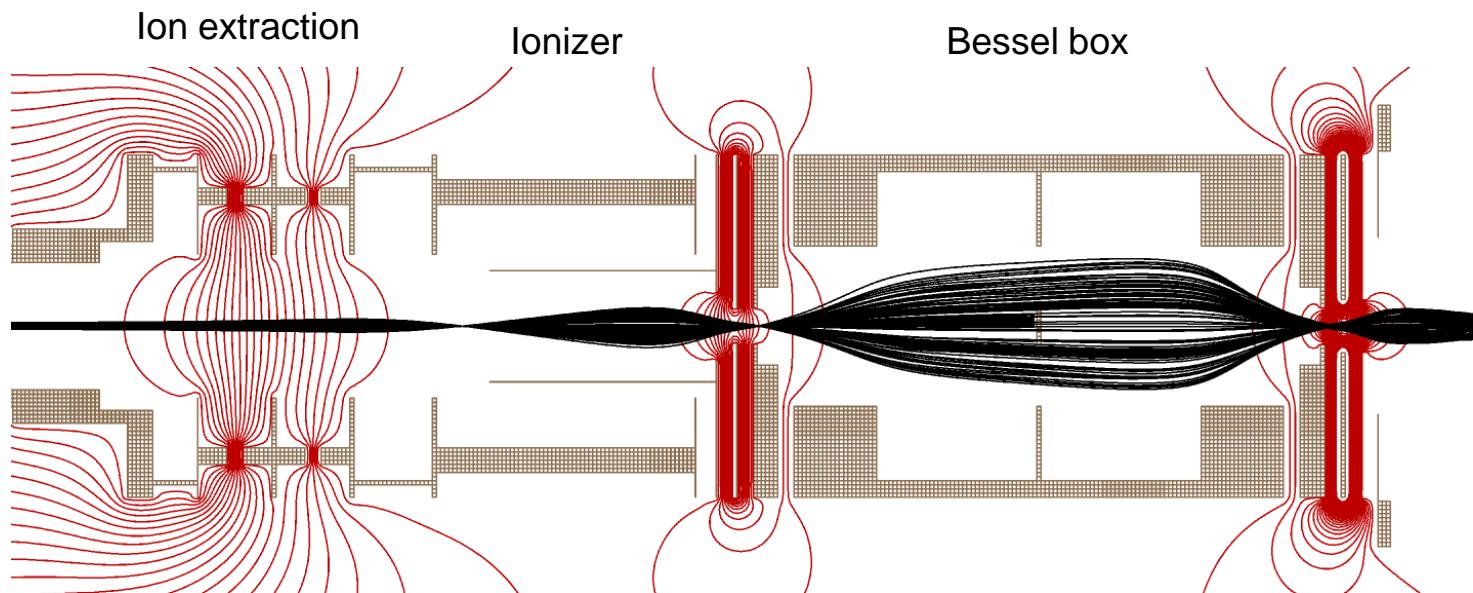


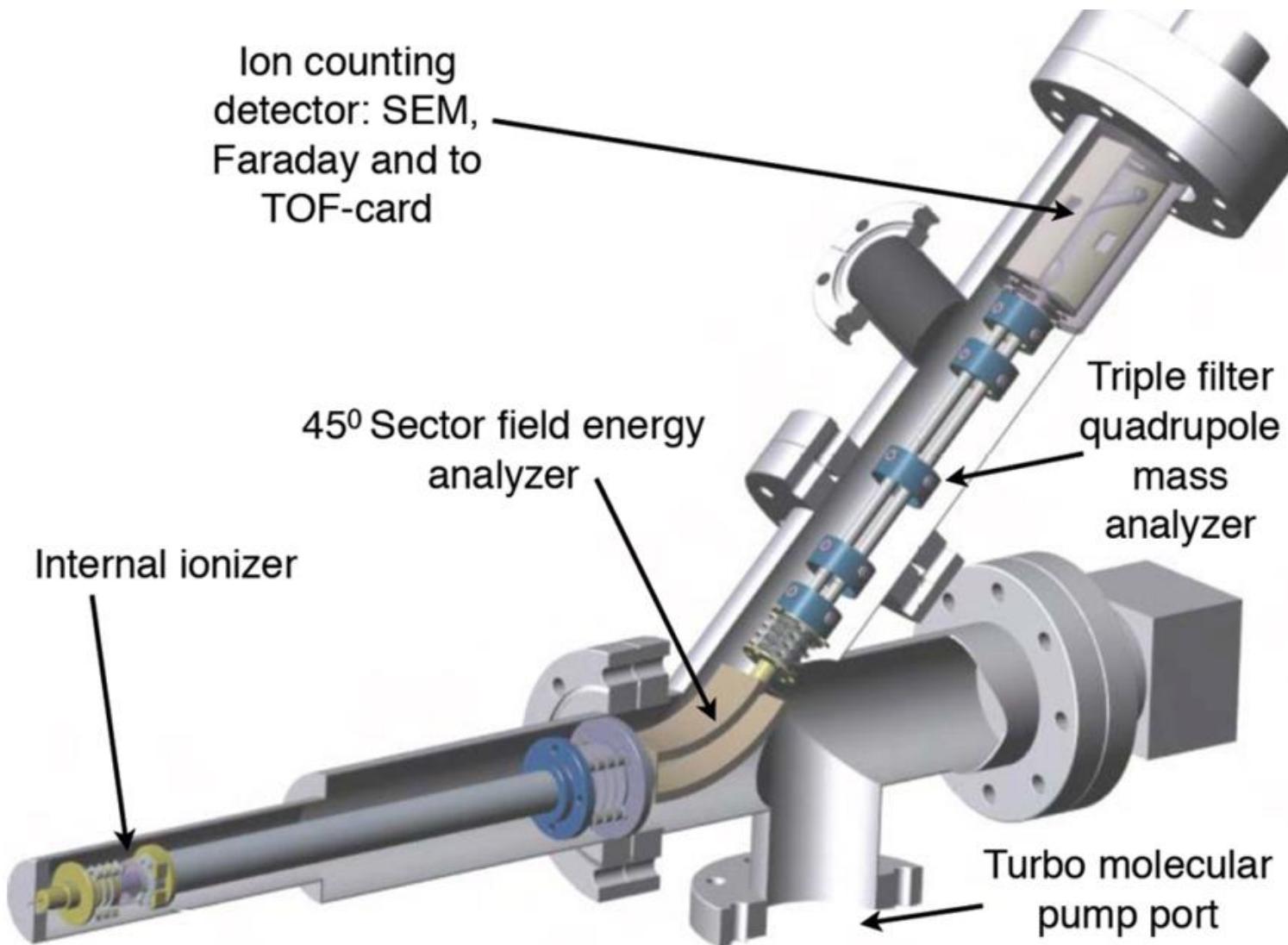
Figure 5. Ion trajectories within (a) the Bessel box (reprinted with permission from [28], copyright 1995, American Institute of Physics) and (b) schematic representation of electrostatic energy analyser (ESA).

Benedikt et al., J. Phys. D: Appl. Phys. **45** (2012) 403001



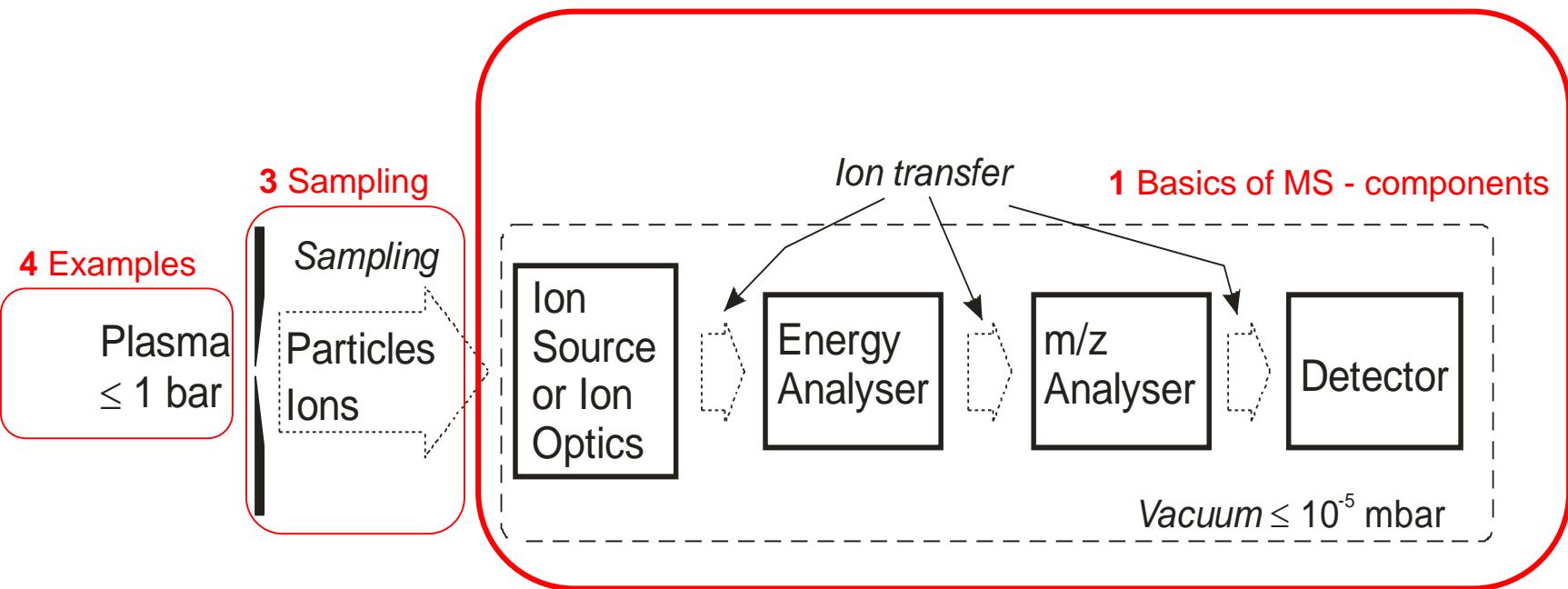
Simulation: Simion 8.1 SW

All components together: for example HIDEN EQP



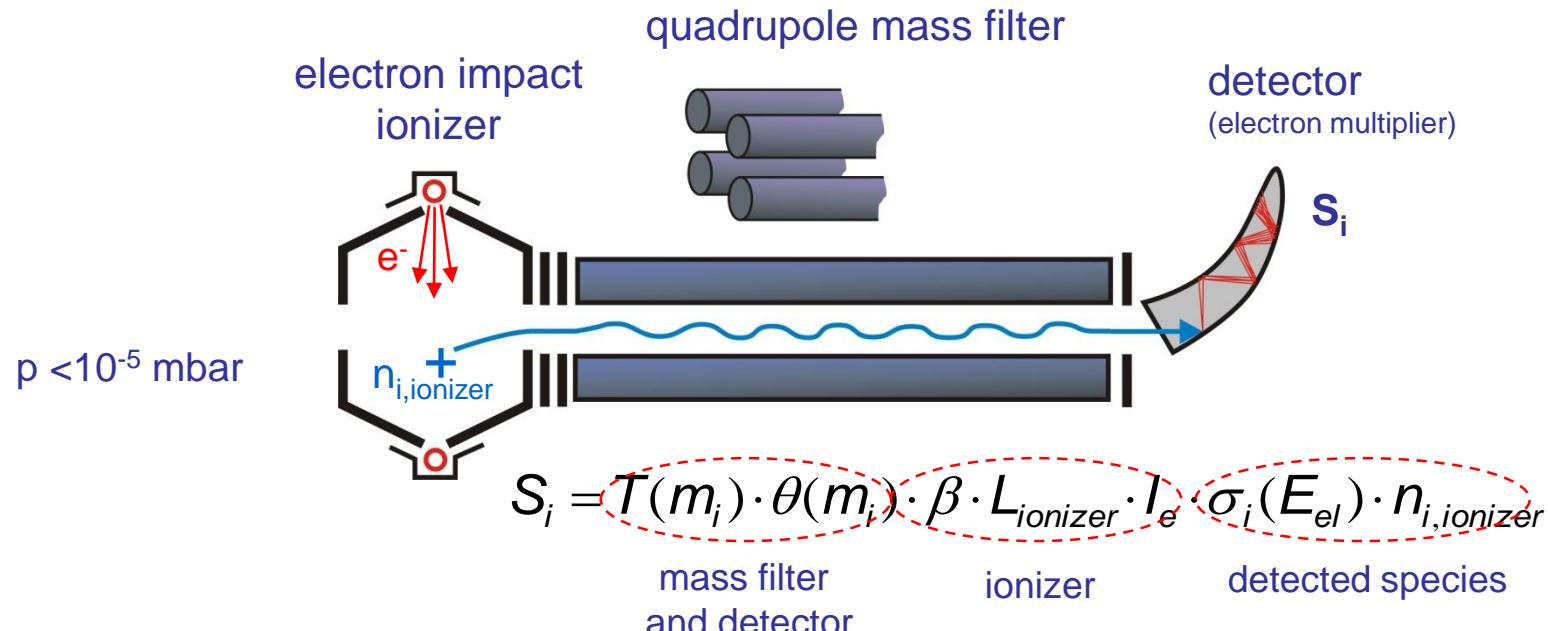
Outline

2 Species identification and quantification



Mass spectrometry

Quantification of neutral species



Signal calibration: measurement of species with known density

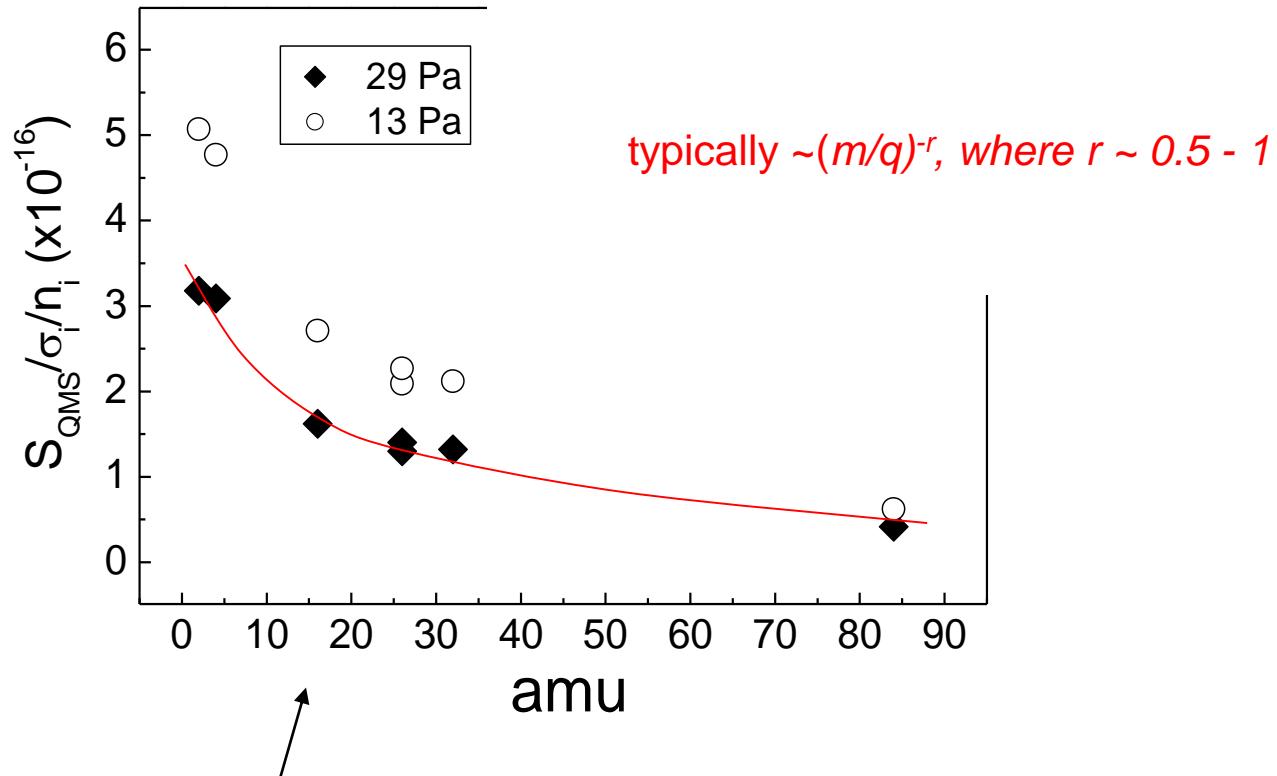
$$S_{cal} = T(m_{cal}) \cdot \theta(m_{cal}) \cdot \beta \cdot L_{ionizer} \cdot I_e \cdot \sigma_{cal}(E_{el}) \cdot n_{cal,ionizer}$$



$$n_{i,ionizer} = F(m_i, m_{cal}) \cdot \frac{\sigma_{cal}(E_{el})}{\sigma_i(E_{el})} \cdot \frac{n_{cal,ionizer}}{S_{cal}} \cdot S_i$$

Mass dependent MS transmission function

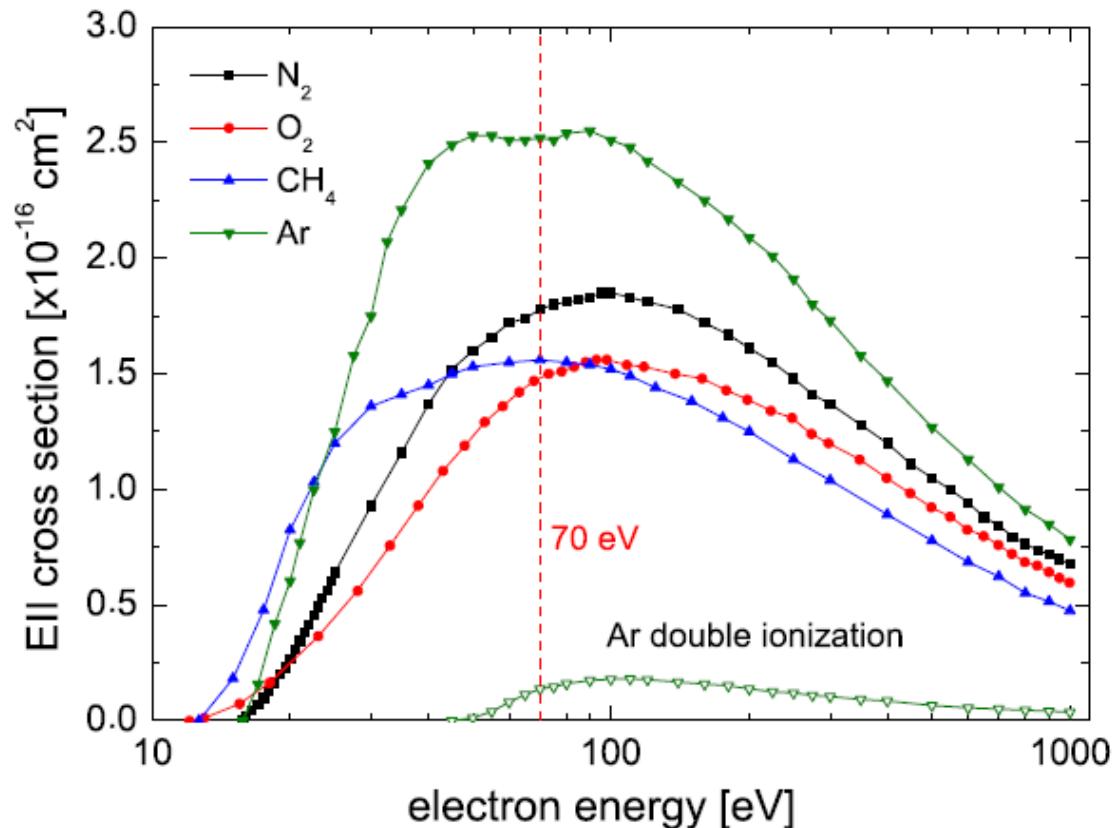
The mass-to-charge (m/q) dependent MS response can be calibrated by stable gases of known densities:



$$n_{i,ionizer} = F(m_i, m_{cal}) \cdot \frac{\sigma_{cal}(E_{el})}{\sigma_i(E_{el})} \cdot \frac{n_{cal,ionizer}}{S_{cal}} \cdot S_i$$

Electron Impact Ionization Cross Section

Known for most of the stable gases



Typical shape

Highest sensitivity at
electron energy
around 70 eV

Figure 2. Electron impact ionization cross-section for different gases as a function of the electron energy. Data taken from [6, 7].

Electron Impact Ionization Cross Section

However: at high E_{el} also dissociation or multiple ionization possible

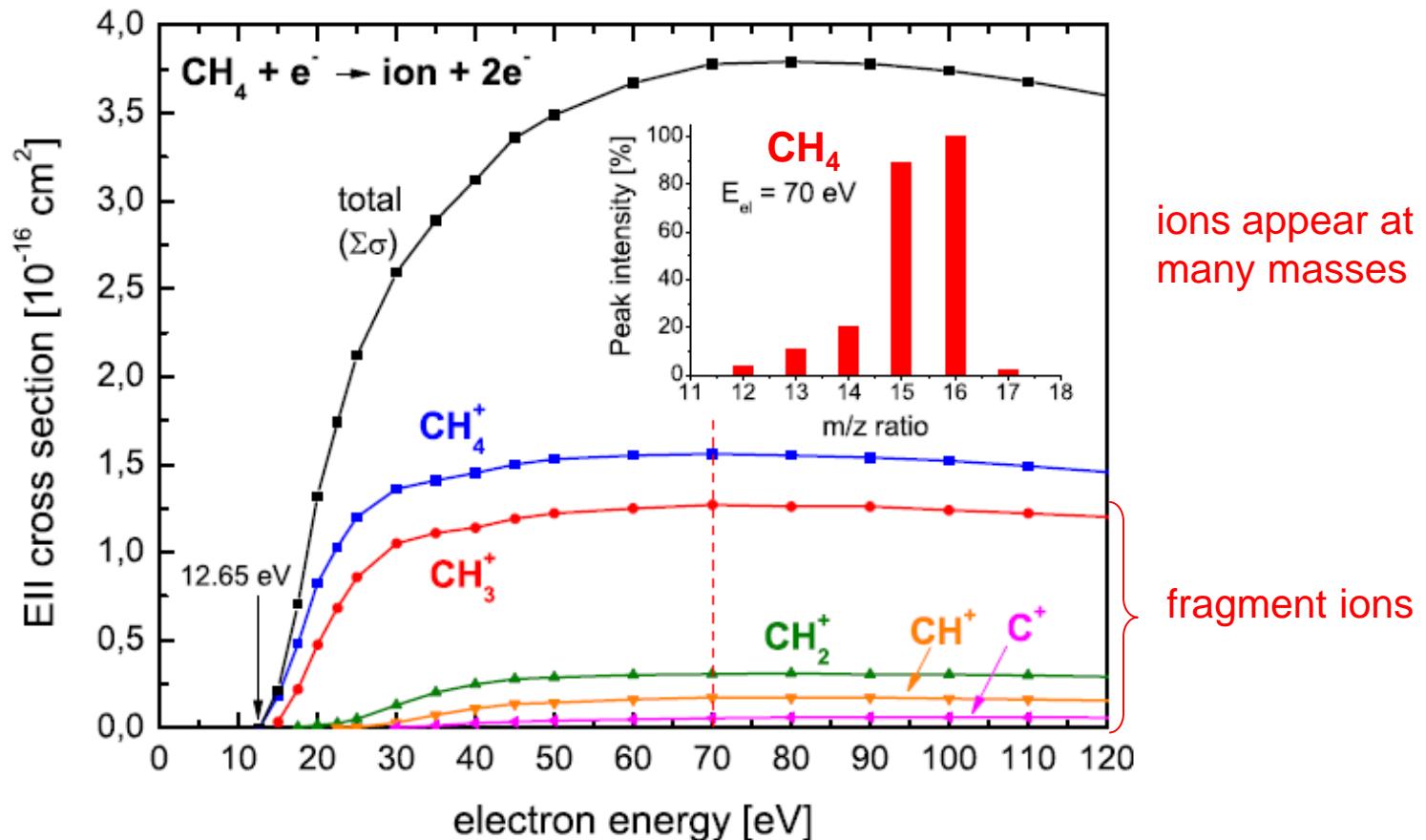
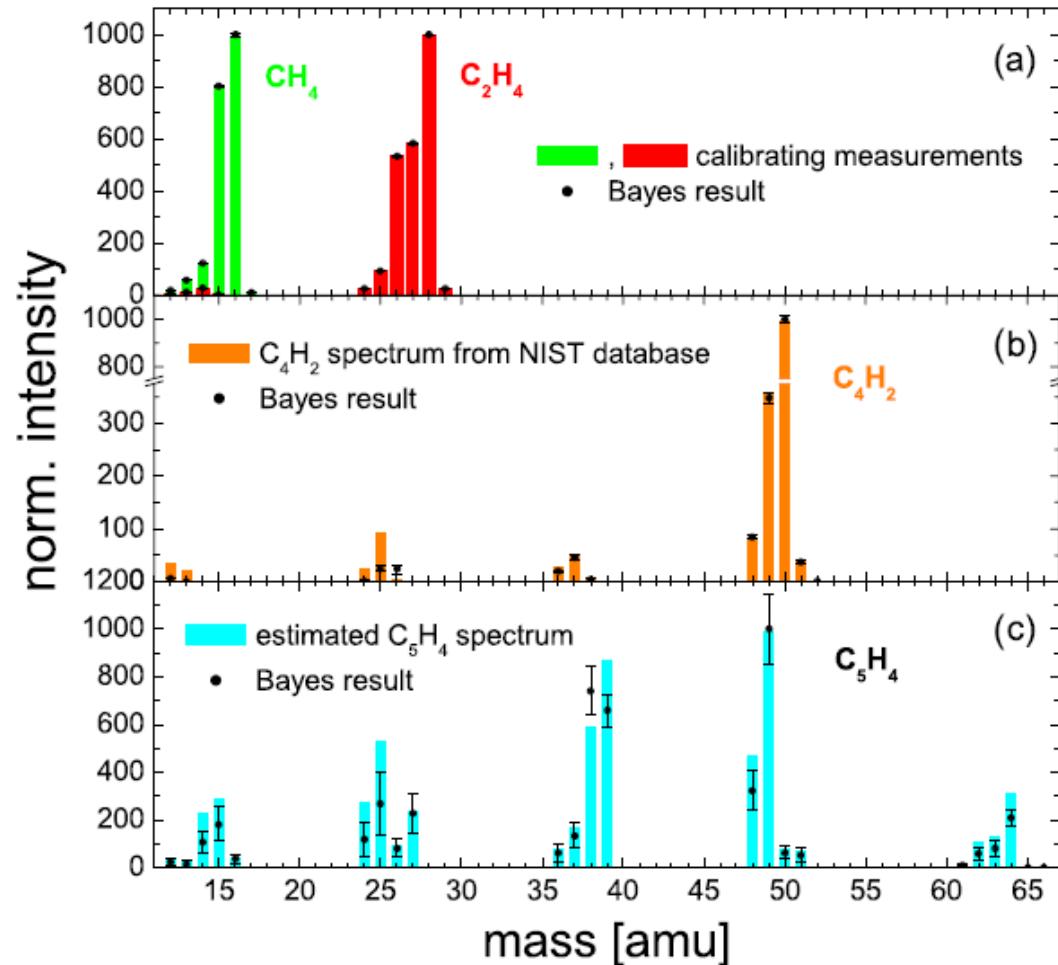


Figure 3. The direct and dissociative EII cross-sections for CH_4 molecule [6] and its CP at $E_{el} = 70$ eV [9].

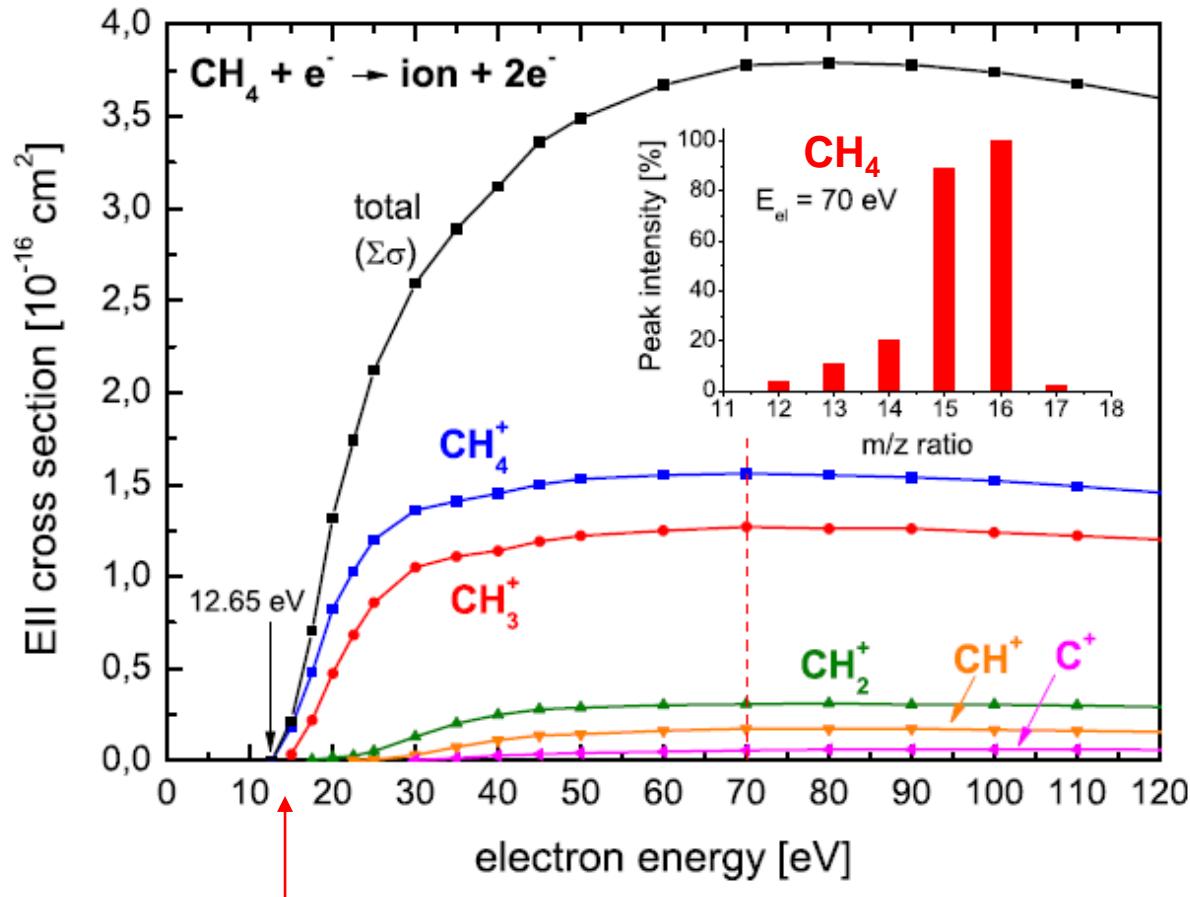
Electron Impact Ionization Cross Section

However: at high E_{el} also dissociation or multiple ionization possible



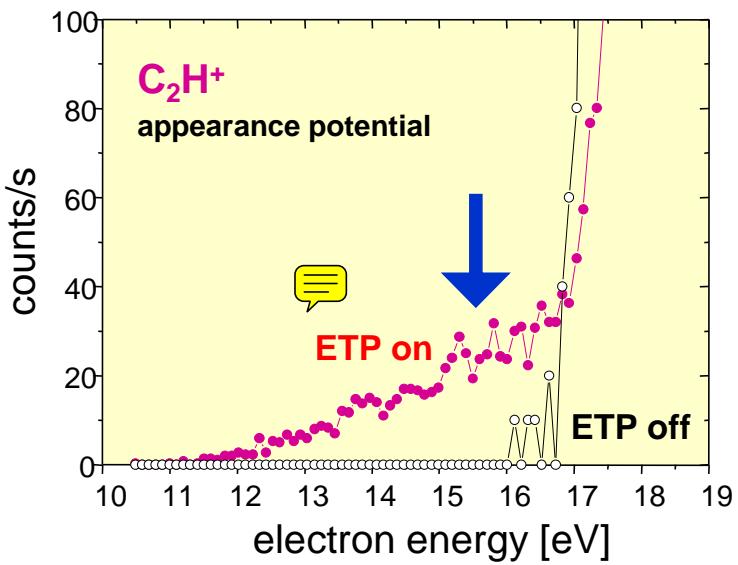
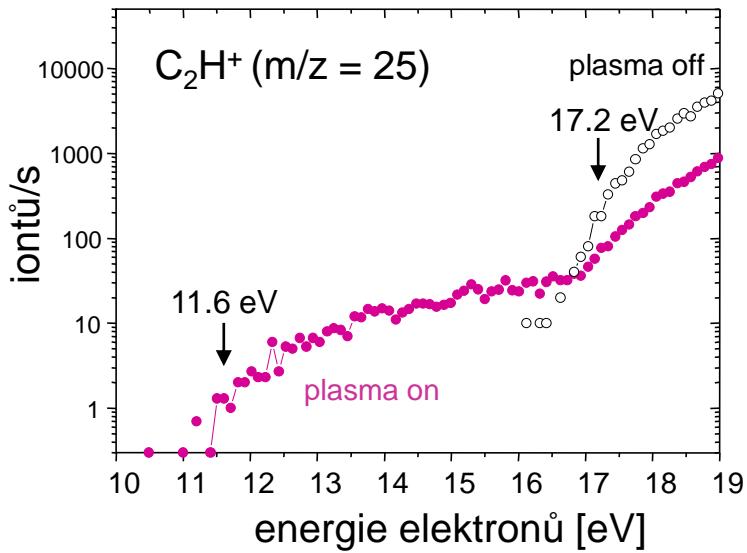
Threshold Ionisation Mass Spectrometry (TIMS)

Possible solution for identification of overlapping mass spectra



measure here, close to the ionization threshold
→ formation of fragment ions limited or avoided

TIMS measurements: C₂H radical



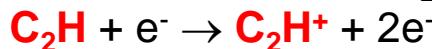
C₂H⁺: ion can originate from two sources:

Dissociative ionization of C₂H₂:



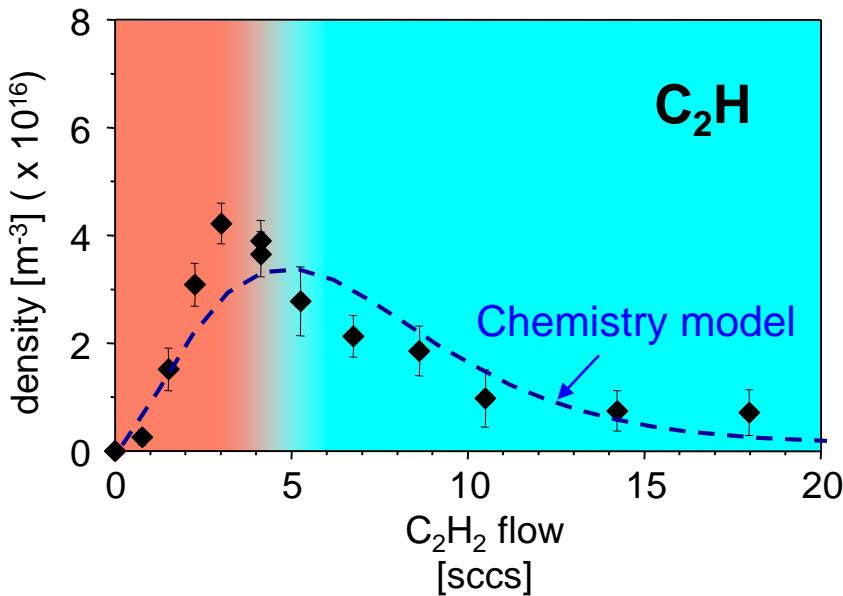
$$17.22 \text{ eV}$$

Direct ionization of C₂H:



$$11.62 \text{ eV}$$

15.5 eV electron energy used

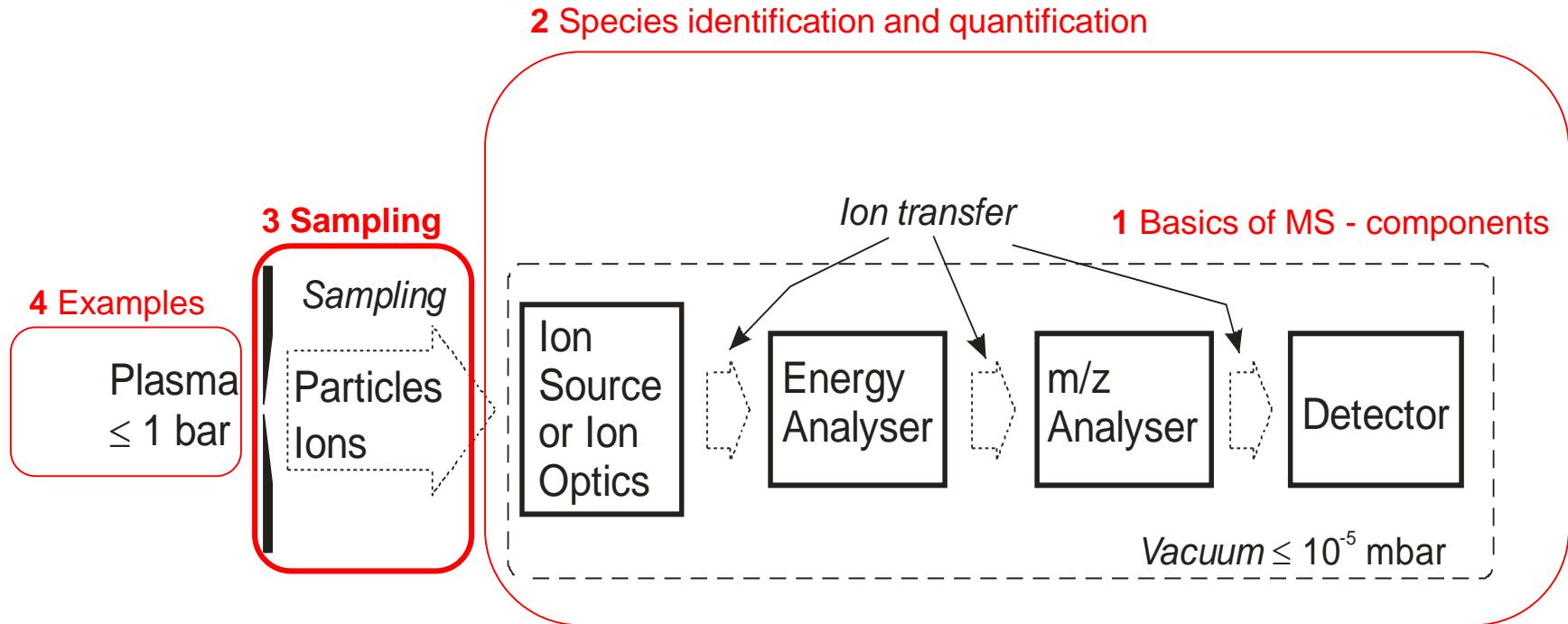


TIMS measurements: other hydrocarbons radicals

TABLE I. Radicals and molecules identified by means of TIMS in an Ar/C₂H₂ ETP, their measured and reported IP, the electron energy used for they measurement and the EII cross section taken from the literature or estimated based on the arguments given in the text. The experimental error of IP is ± 0.2 eV if not indicated otherwise. The literature source for IP values is Ref. 30 and references therein.

Species (amu)	Measured IP [eV]	Literature IP [eV]	E_{electron} (eV)	$\sigma_I(E) \times 10^{-16}$ (cm ²)	
C (12)	11.3	11.26	19	0.96/0.84 ^a	ETP - expanding thermal plasma
CH (13)	10.5	10.64	19	0.72/0.90 ^a	
CH ₂ (14)	10.5	10.35	14	0.31/0.43 ^a	
CH ₃ (15)	9.9	9.84	13	0.26/0.37 ^a	
CH ₄ (16)	12.6	12.61	17	0.60/0.51 ^a	
C ₂ (24)	11.5	11.41	18	0.73 ^a	
C ₂ H (25)	11.7	11.61	15.5	0.45 ^a	
C ₂ H ₂ (26)	11.4	11.40	14	0.31	
C ₃ (36)	12.1	11–13 ^b	14	0.23 ^a	
C ₃ H (37)	9.7	9.8	15	0.59 ^a	
C ₃ H ₂ (38)	9.2	8.7/9.15/10.43 ^c	12	0.33 ^a	
C ₃ H ₄ (40)	10.3	10.37	13	0.31 ^a	
C ₄ (48)	11.9±0.5	12.6	18	0.61 ^a	
C ₄ H (49)	11.7±0.5	Not known	15	0.39 ^a	
C ₄ H ₂ (50)	10.2	10.17	50	4.8 ^d	
C ₅ (60)	11.4±0.5	12.3	17	0.63 ^a	
C ₅ H (61)	9.8	Not known	18	0.89 ^a	
C ₅ H ₄ (64)	10.0	8.67/9.5/10.1 ^c	13	0.35 ^a	
C ₅ H ₆ (66)	10±1	8.0–9.3	13	0.35 ^a	
C ₆ H ₂ (74)	Not measured	9.50	50	7.1 ^d	
C ₆ H ₆ (78)	Not measured	8.1–9.9 ^c	50	Not estimated	

Outline



How to connect measured ionizer density with density in the plasma?

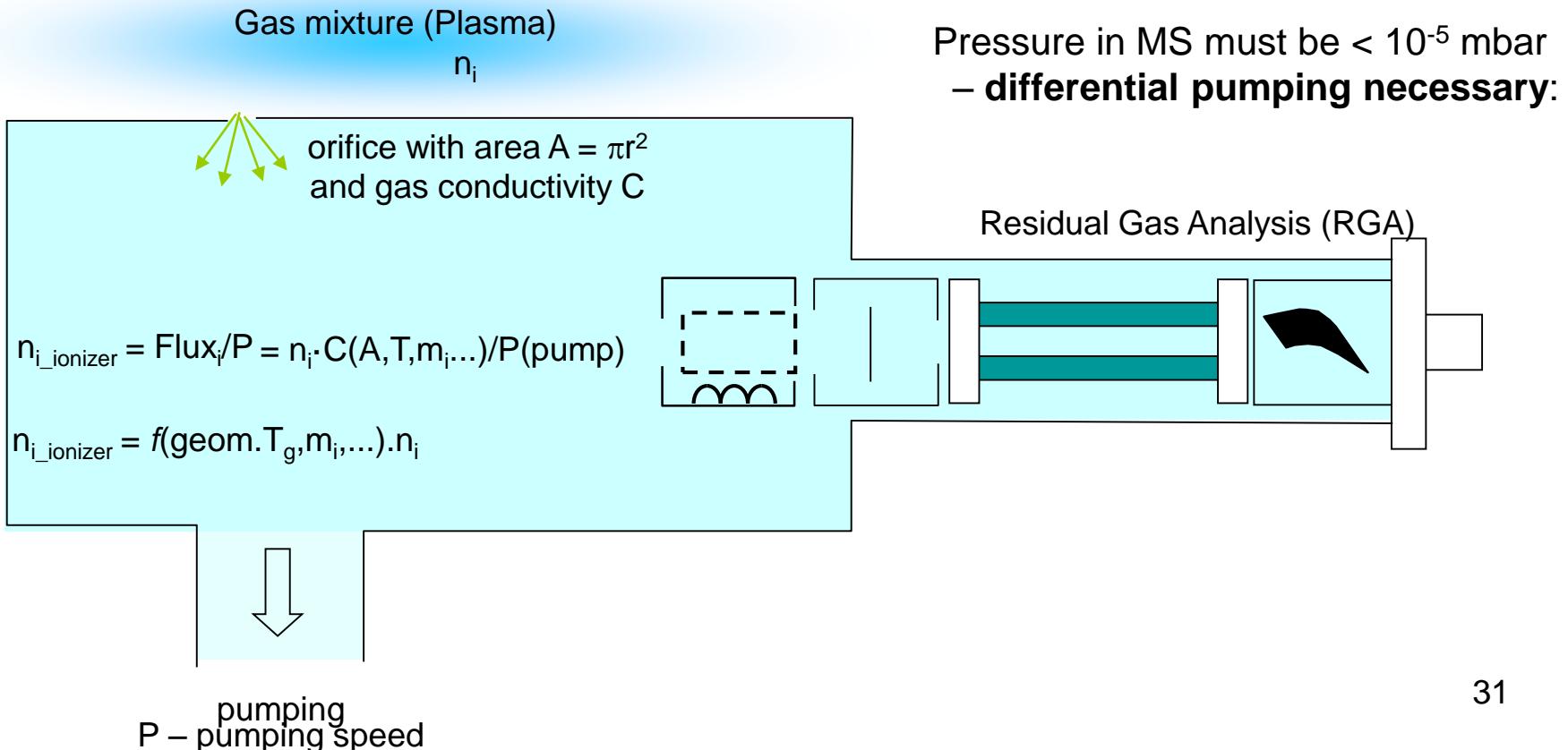
What is the use of differential pumping...?

How to sample ions?

Measurement of stable species

$$n_{i,\text{ionizer}} = F(m_i, m_{\text{cal}}) \cdot \frac{\sigma_{\text{cal}}(E_{\text{el}})}{\sigma_i(E_{\text{el}})} \cdot \frac{n_{\text{cal,ionizer}}}{S_{\text{cal}}} \cdot S_i$$

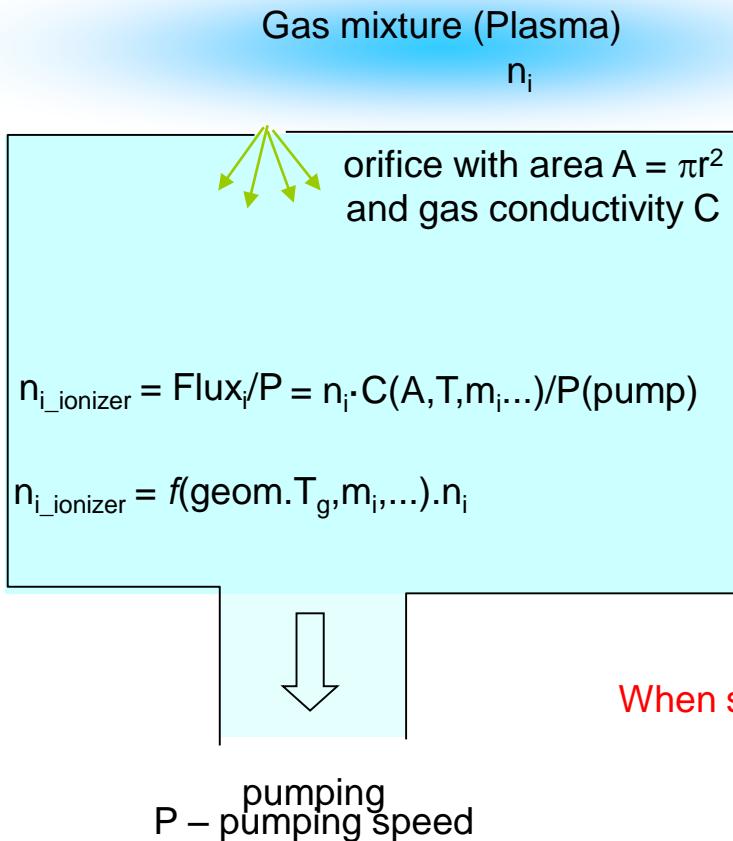
How to connect it with density at the sampling orifice? → differential pumping



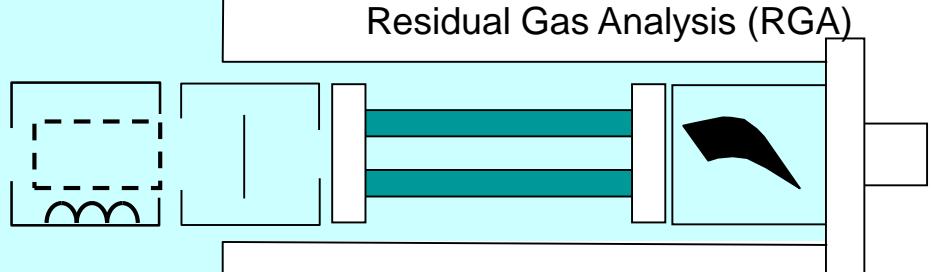
Measurement of stable species

$$n_{i,\text{ionizer}} = F(m_i, m_{\text{cal}}) \cdot \frac{\sigma_{\text{cal}}(E_{\text{el}})}{\sigma_i(E_{\text{el}})} \cdot \frac{n_{\text{cal,ionizer}}}{S_{\text{cal}}} \cdot S_i$$

How to connect it with density at the sampling orifice? → differential pumping



Pressure in MS must be $< 10^{-5}$ mbar
– **differential pumping necessary:**



However:
When species reactive at the surface ($\beta \rightarrow 1$) → lost at the surface →
 $n_{i,\text{ion.}} \rightarrow \text{small}$
RGA does not work for the reactive species!

Measurement of reactive neutrals: Molecular Beam Sampling

$$n_{i,\text{ionizer}} = F(m_i, m_{\text{cal}}) \cdot \frac{\sigma_{\text{cal}}(E_{\text{el}})}{\sigma_i(E_{\text{el}})} \cdot \frac{n_{\text{cal,ionizer}}}{S_{\text{cal}}} \cdot S_i$$

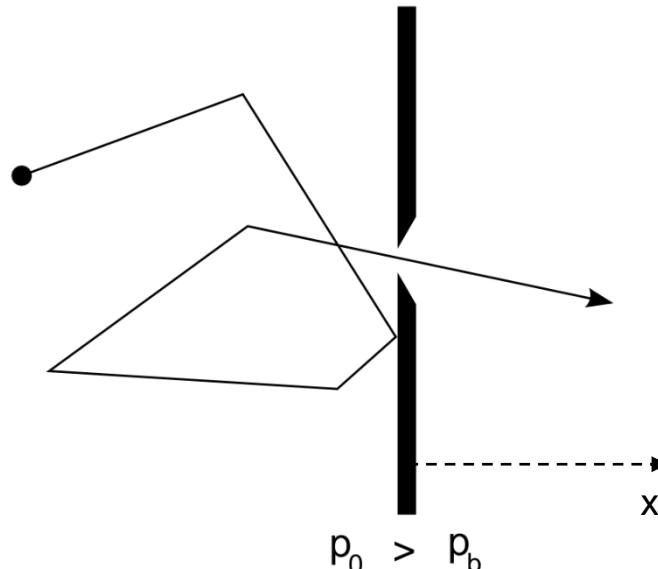


How to connect it with density at the sampling orifice? → molecular beam sampling

Formation of molecular beam depends on Knudsen number $K_n = \frac{\lambda}{d}$

$K_n > 1$

Free molecular flow without collisions



Density in the beam easy to determine:

$$n_{\text{Beam}}(x) = \frac{1}{4} \left(\frac{d}{x} \right)^2 n_0$$

Orifice aspect ratio important
- sharp edge needed!

x (position of the ionizer) should be as small as possible!

Measurement of reactive neutrals: Molecular Beam Sampling

Multiple differential pumping stages + formation of molecular beam

→ Reactive species measurement possible

Ionizer density:

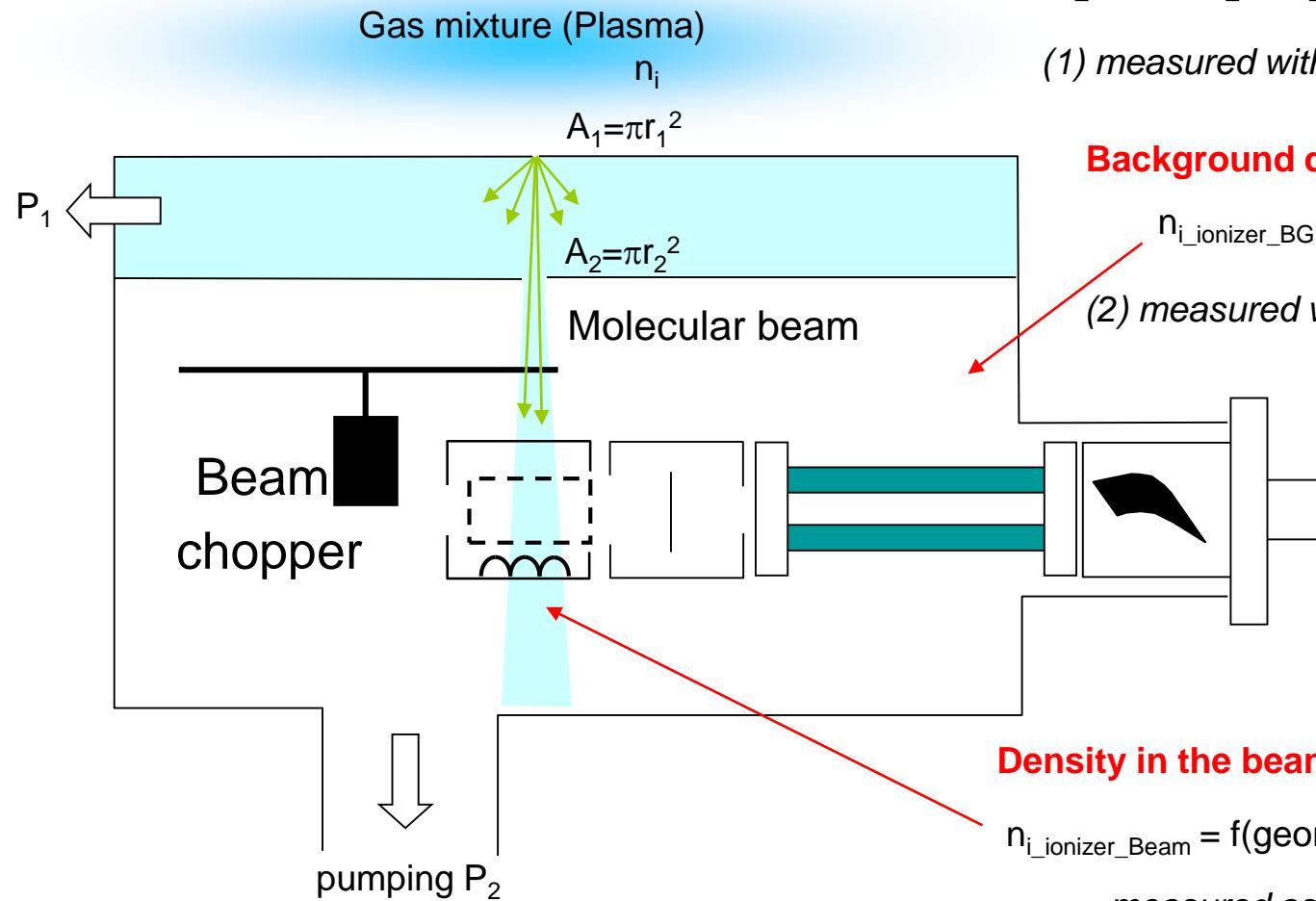
$$n_{i_ionizer} = n_{i_ionizer_BG} + n_{i_ionizer_Beam}$$

(1) measured without chopper blocking the beam

Background density:

$$n_{i_ionizer_BG} = n_i \cdot C_1 \cdot C_2 / P_1 P_2$$

(2) measured with chopper blocking the beam

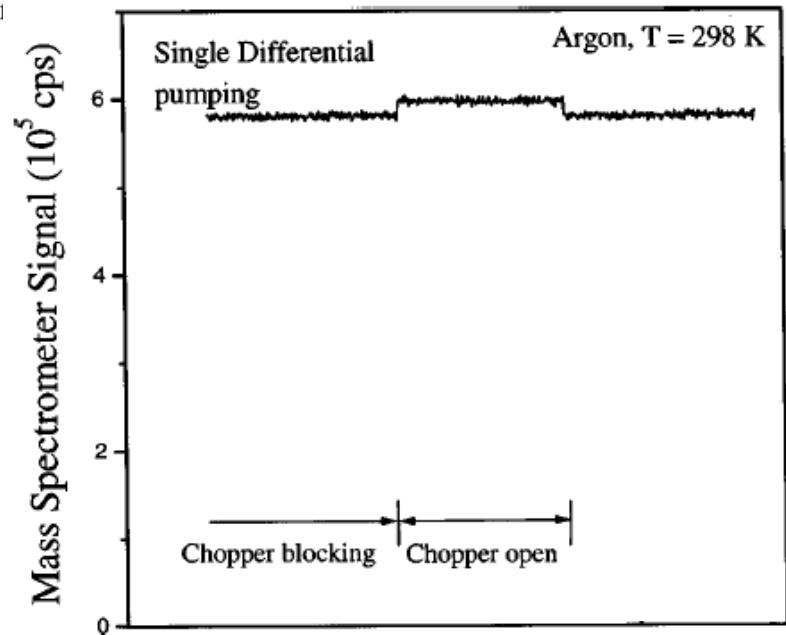
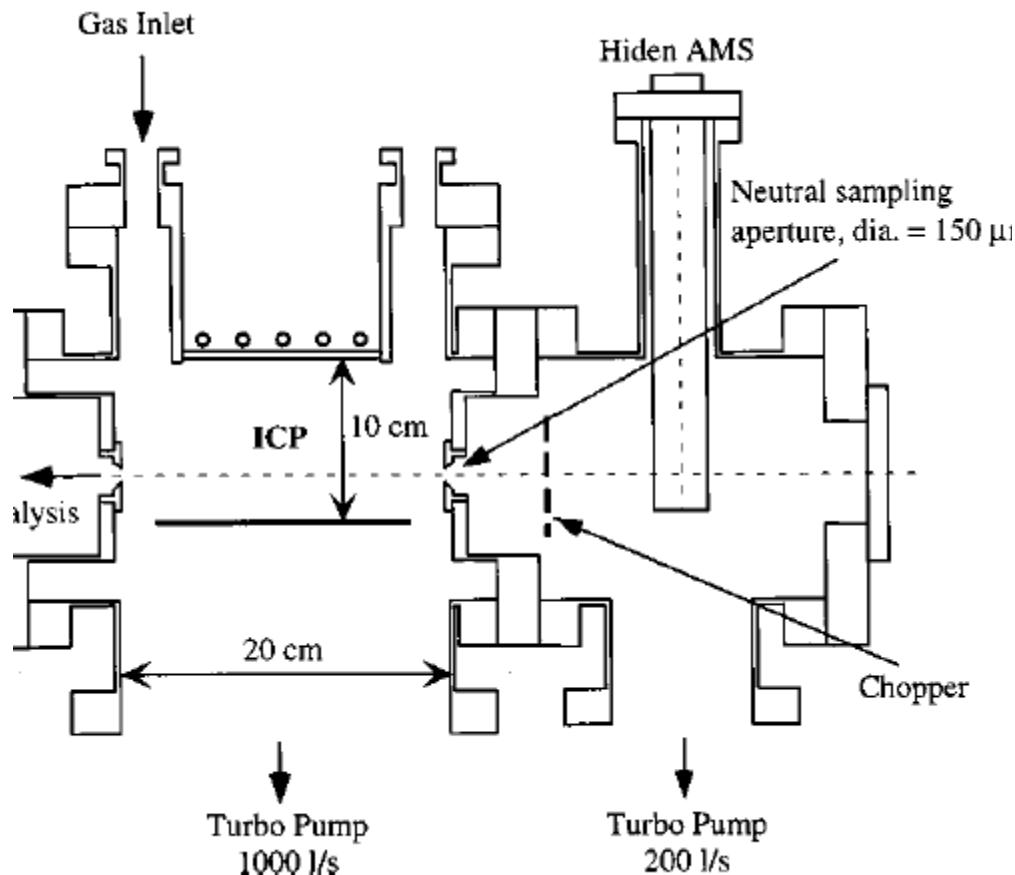


$$n_{i_ionizer_Beam} = f(\text{geom.}, T_g, m_i, m_{cg}, \dots) \cdot n_i$$

measured as difference (1) – (2)

Example: CF_x species measurement

Single stage differential pumping

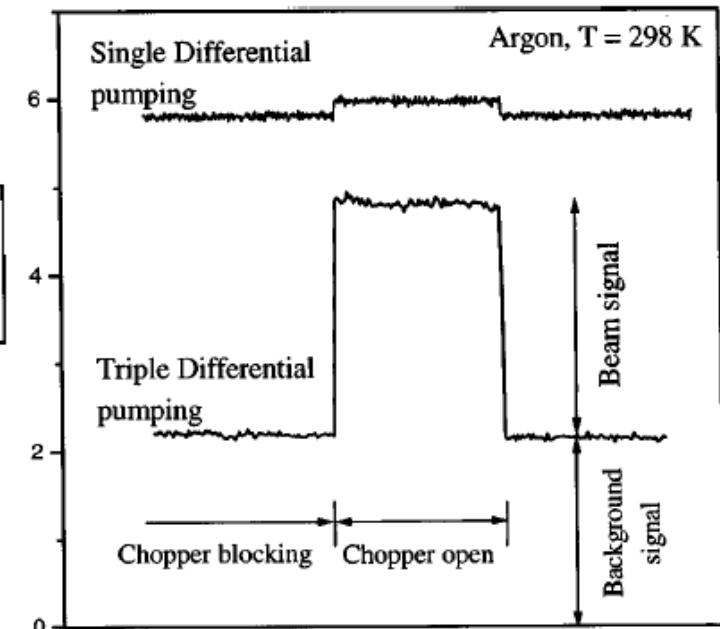
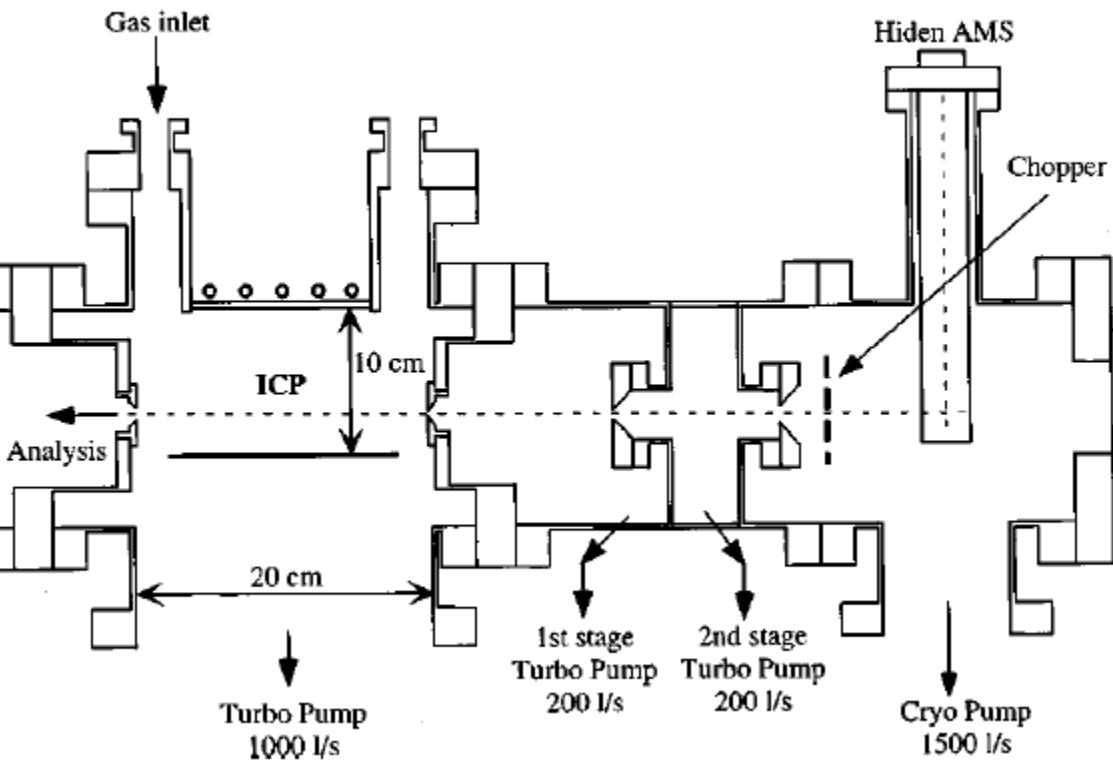


$$n_{i_ionizer_BG} = n_i \cdot C(A, T) / P$$

$$n_{i_ionizer_Beam} = 1/4 \cdot n_i \cdot (r/x)^2$$

Example: CF_x species measurement

Tripple stage differential pumping



$$n_{i_ionizer_BG} = n_i \cdot C_1 \cdot C_2 \cdot C_3 / (P_1 P_2 P_3)$$

$$n_{i_ionizer_Beam} = 1/4 \cdot n_i \cdot (r/x)^2$$

Comparison beam x background densities

J. Phys. D: Appl. Phys. **45** (2012) 403001

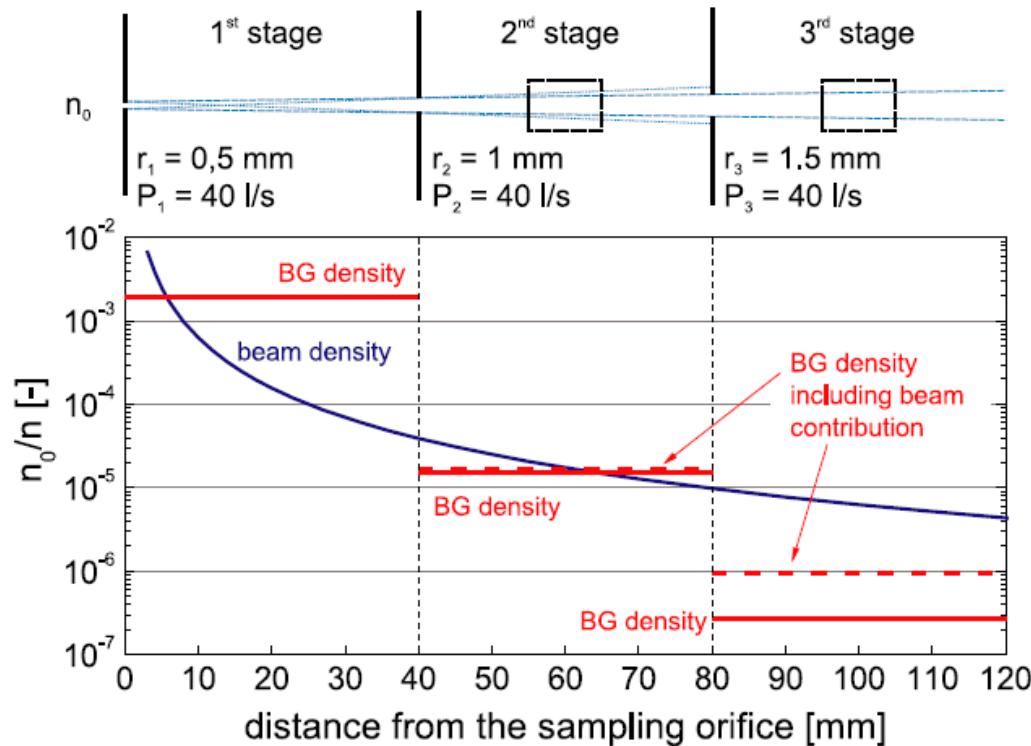


Figure 11. Model calculation of beam and BG densities in the differentially pumped stages of the sampling system. The BG density is calculated for two cases: (i) solid red line: the beam particles are not taken into account as a source of BG density and (ii) dashed red line: the beam particle are added as a source of BG particles.

Molecular beam sampling – ionizer issue

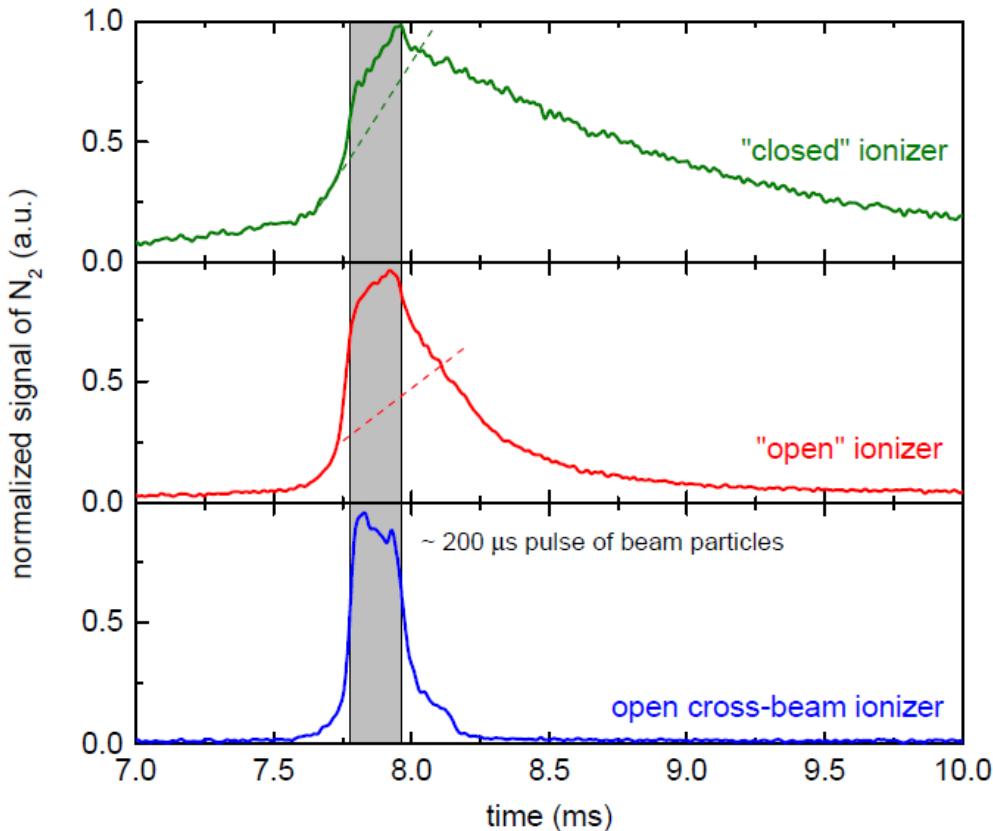


Figure 6. Time resolved normalized MS signals at mass 28 (nitrogen molecules) of a pulsed MB with pulse length of $200 \mu\text{s}$ as measured with an “open” and “closed” ionizer, after [32]. Additionally, the signal obtained with modified ionizer, where 40 % of the surface area of the closed ionizer has been replaced by a mesh. The beam is generated with the chopper shown in Fig. 4.

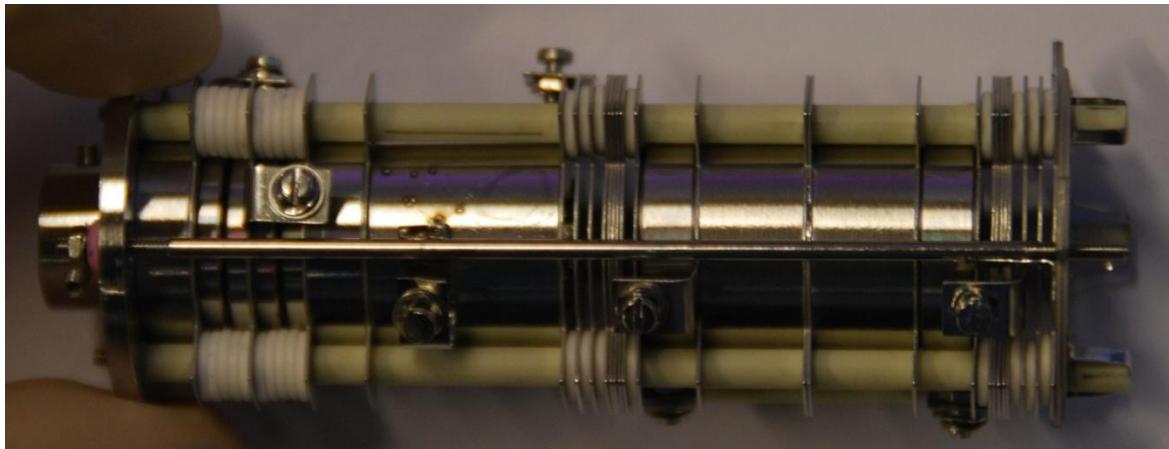
Measurement of the pulsed molecular beam have shown that the “closed” ionizer can be filled with “beam particles”

→ problem in the calibration!

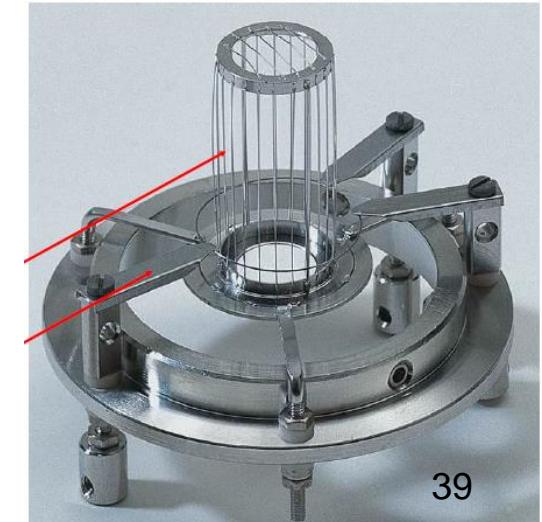
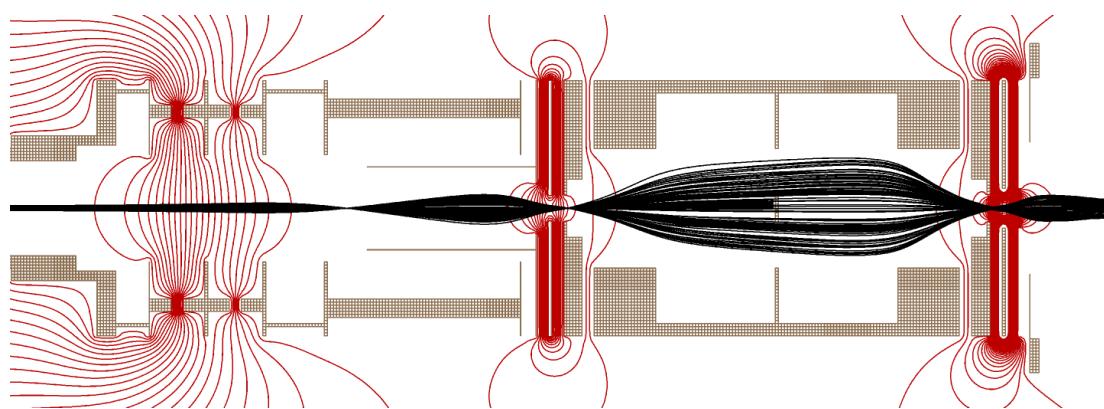
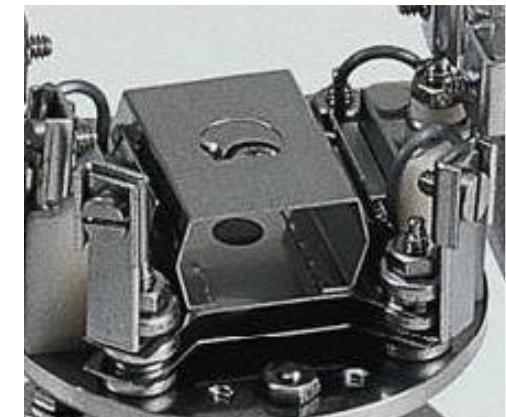
S. Große-Kreul et al.,
accepted in J. Phys. D

Issue of a closed and open ionizer

closed ionizer

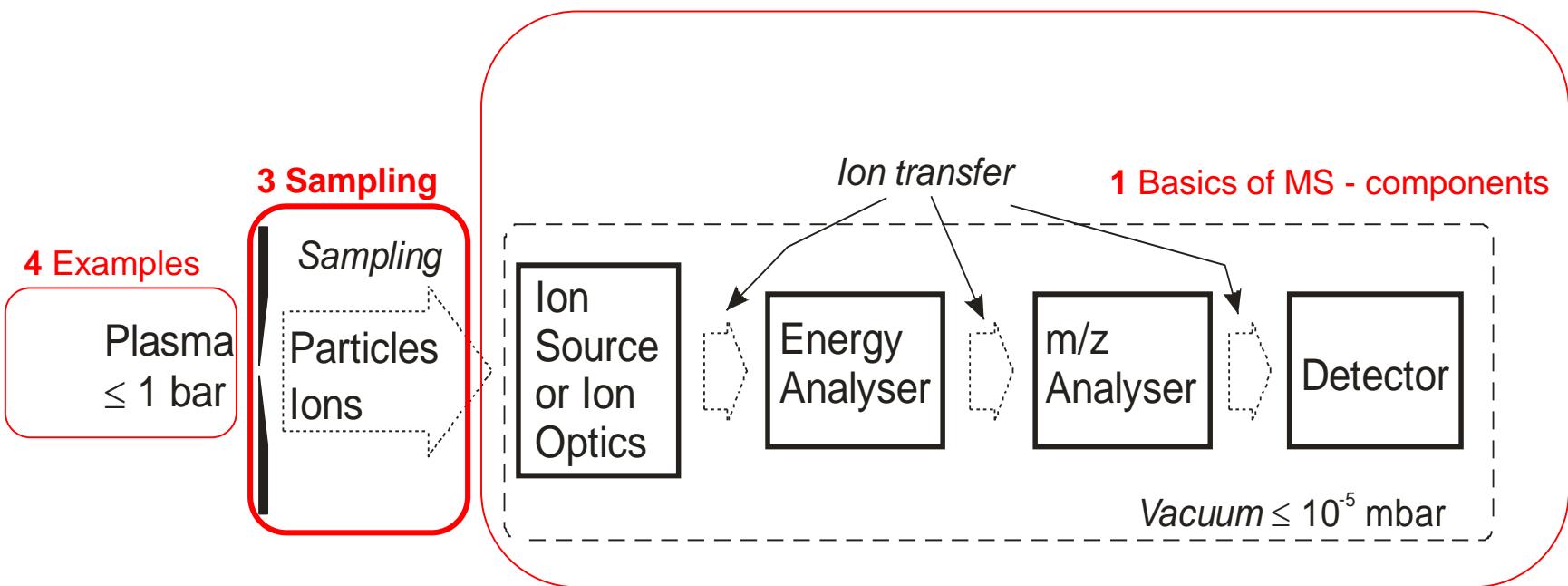


open ionizer



Outline

2 Species identification and quantification

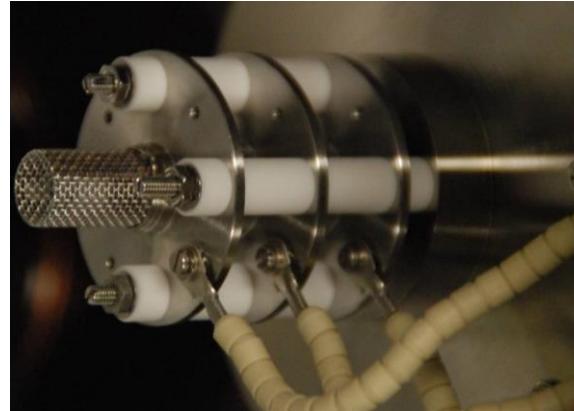
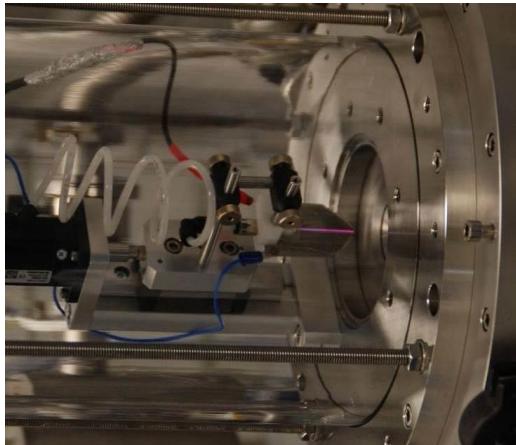


How to connect measured ionizer density with density in the plasma?

What is the use of differential pumping...?

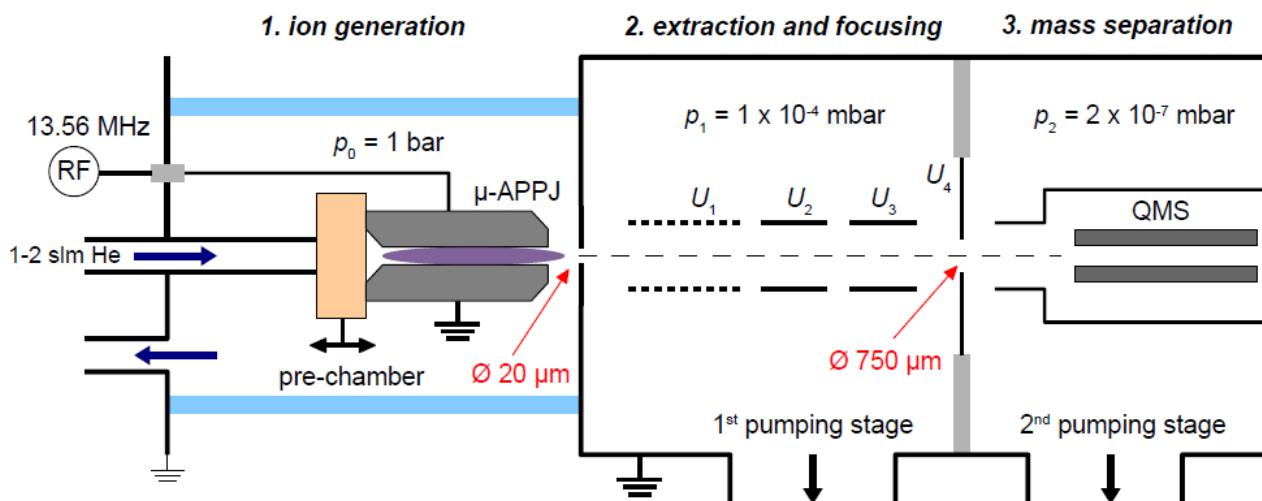
How to sample ions?

Mass spectrometry of ions



Ions manipulated and focused into MS with ion optics

No ionization and no background correction are needed



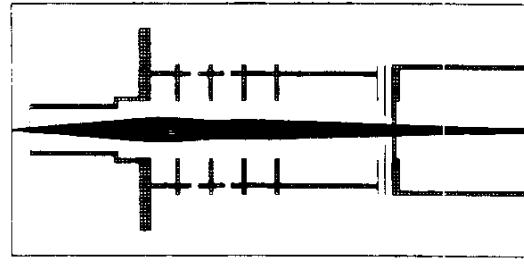
More diff. pumping stages needed only for measurement of atm. plasmas

But only relativ fluxes are measured, not densities!

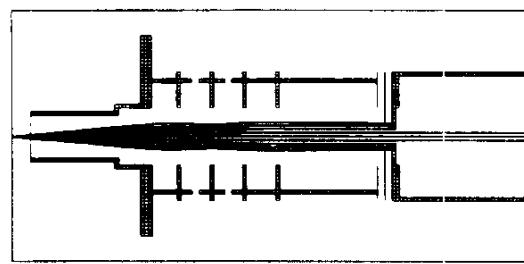
The ion lenses have to be properly tuned and calibrated

Tuning of ion lenses – depends on ion energy

avoiding chromatic (energy) aberration



(a)



(b)

Fig. 2. Calculated ion trajectories in the case where lens 1 suffers from chromatic aberration ($V_{\text{Ext}} = -5 \text{ V}$, $V_{L1} = -100 \text{ V}$) at different ion energies: (a) 10 eV, (b) 20 eV. The voltage V_{L2} amounts -200 V . The angle between subsequent ion trajectories is 1.5° .

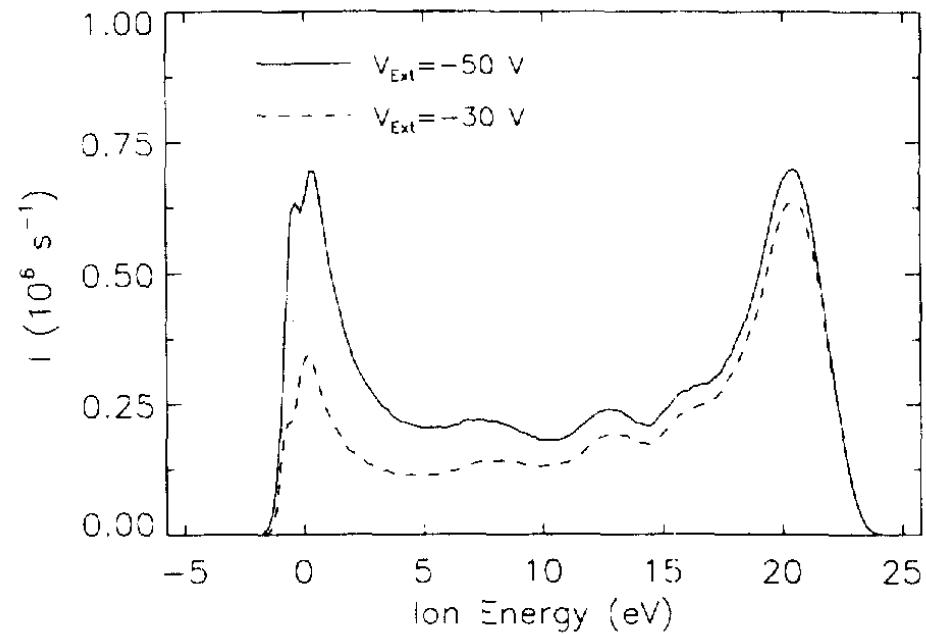
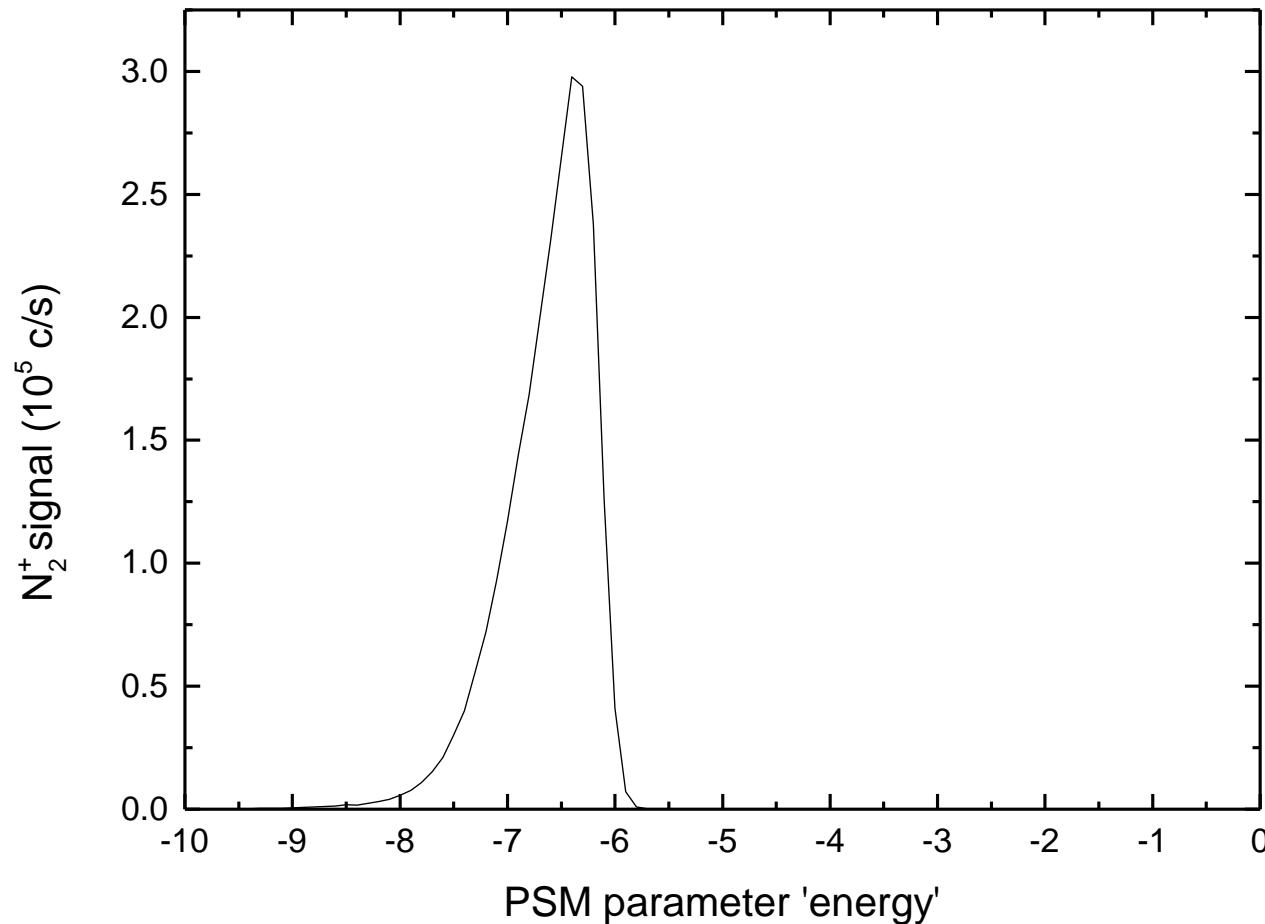


Fig. 6. Ion-energy distributions of Ar^+ in argon, measured with two different $V_{\text{Ext}} - V_{L1}$ combinations: solid line, $V_{\text{Ext}} = -50 \text{ V}$; dashed line, $V_{\text{Ext}} = -30 \text{ V}$. The power input into the reactor is 30 W at a gas pressure of 5 Pa. Along the x-axis V_{Ext} is plotted.

Calibration of the ion optics - energy scale

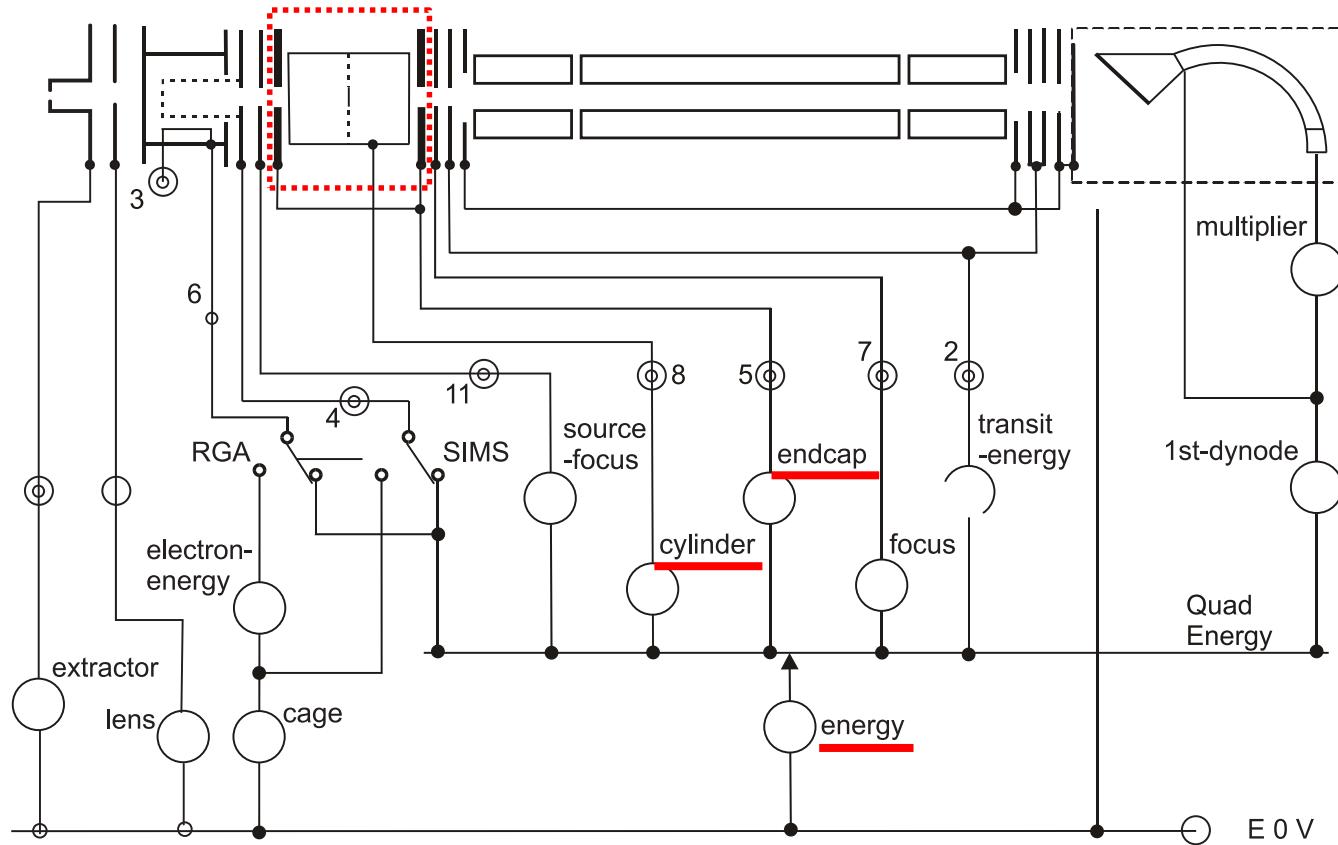
He/N₂ atmospheric plasma



Negative → does not make really sense...

Experimental setup

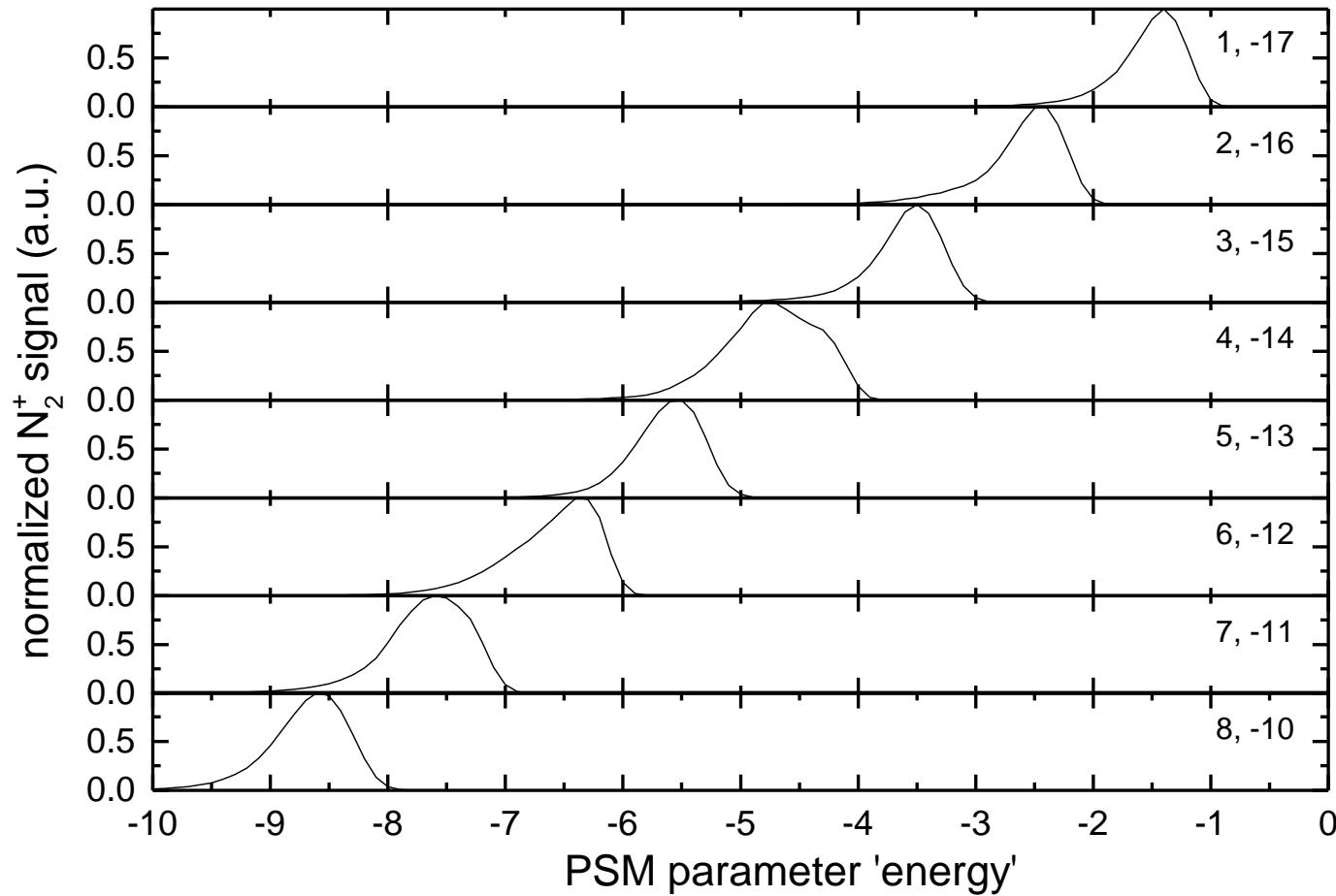
PSM mass spectrometer from HIDEN Analytical



Energy filter: „Bessel Box“ with parameters: *cylinder, endcap, energy*

Results

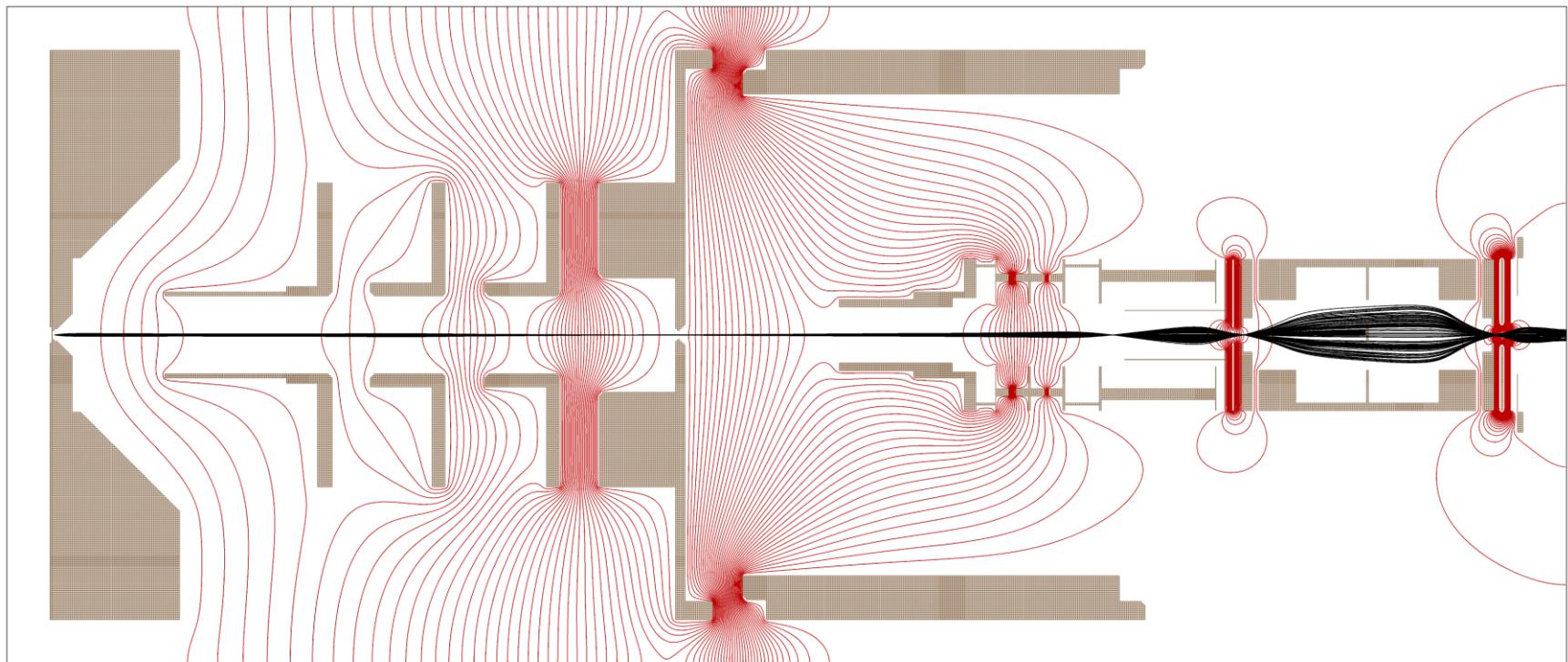
Variation of the Bessel-box parameters: *cylinder, endcap, energy*



What is the real ion energy?

Simulation of ion optics in the sampling system

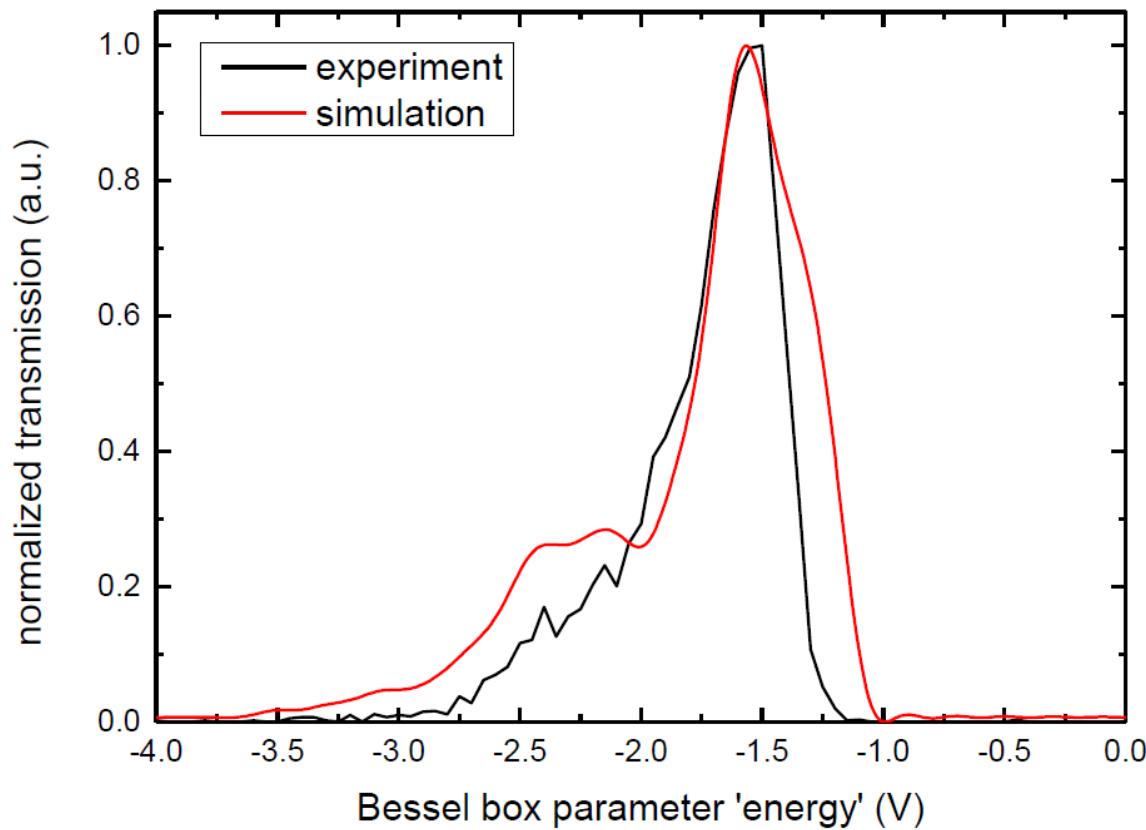
SIMION simulations



Real ion energy to maximize the transmission efficiency with all tuned MS parameters: $E_{\text{ions}} = +0.8 \text{ eV}$

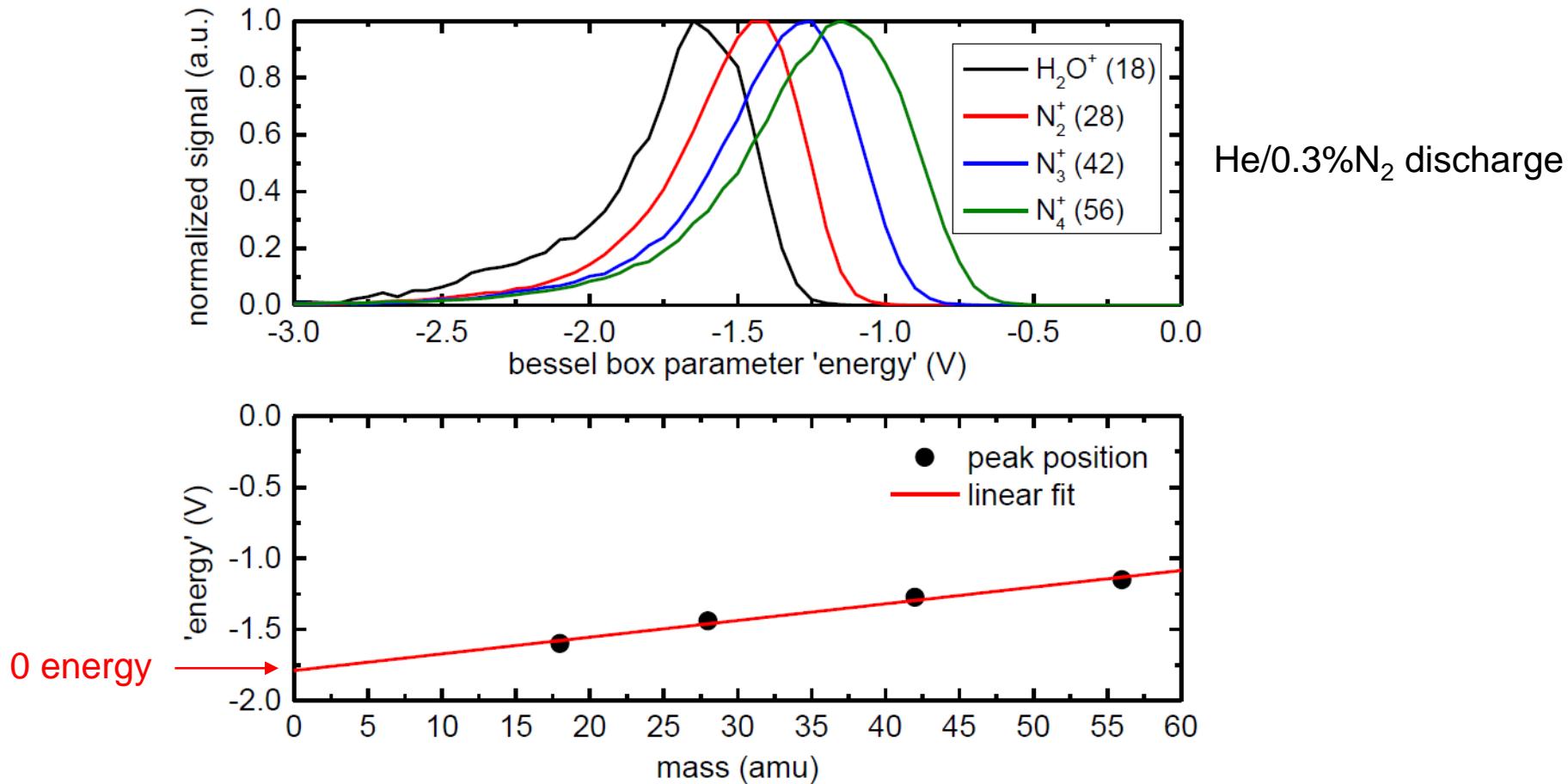
Simulation of ion optics x measurement

SIMION simulations



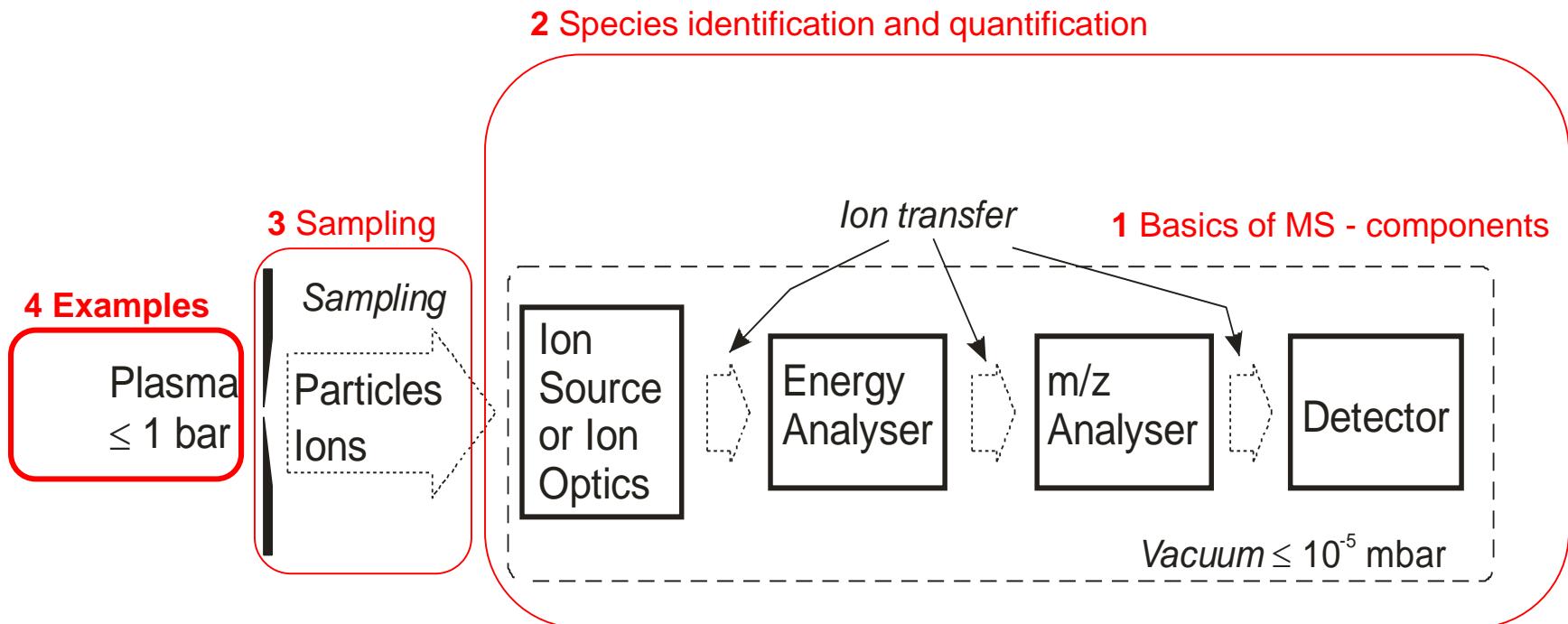
Real ion energy to maximize the transmission efficiency with all tuned MS parameters: $E_{\text{ions}} = +0.8 \text{ eV}$

Ion measurement from atmospheric plasmas



Seeded He beam – all ions reach the same velocity in the expansion – energy scales linearly with their mass!

Outline



Example: analysis of an etch process of a-C:H

Gas on ($\text{Ar} + \text{O}_2$)

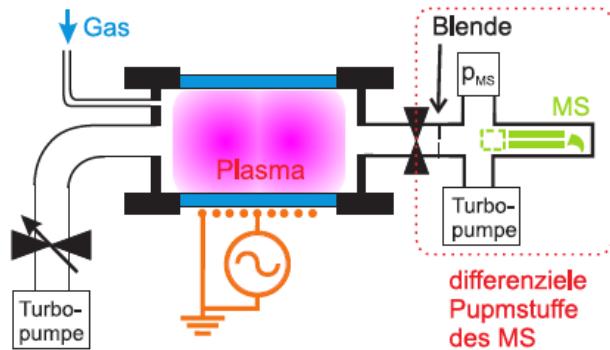
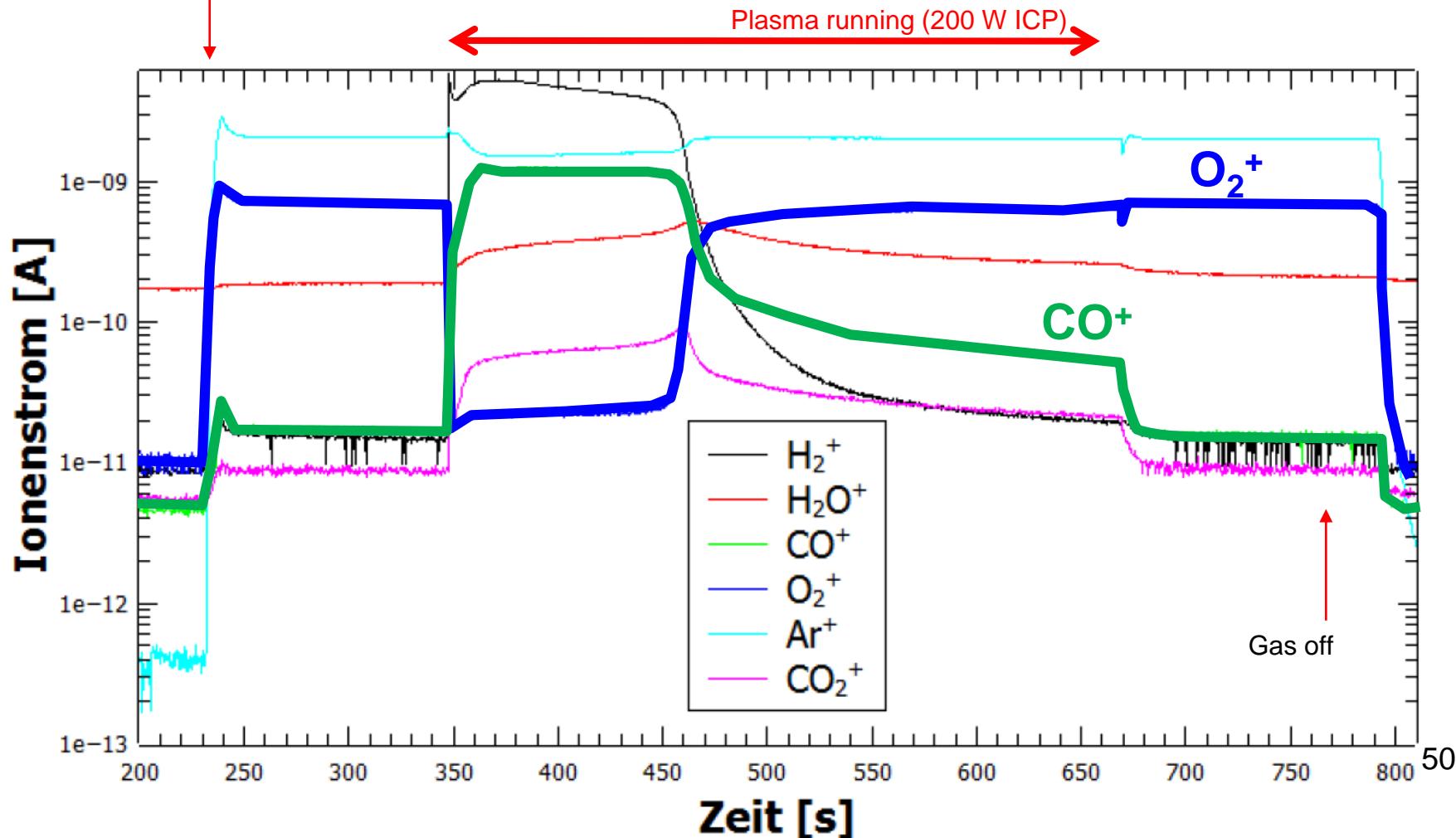
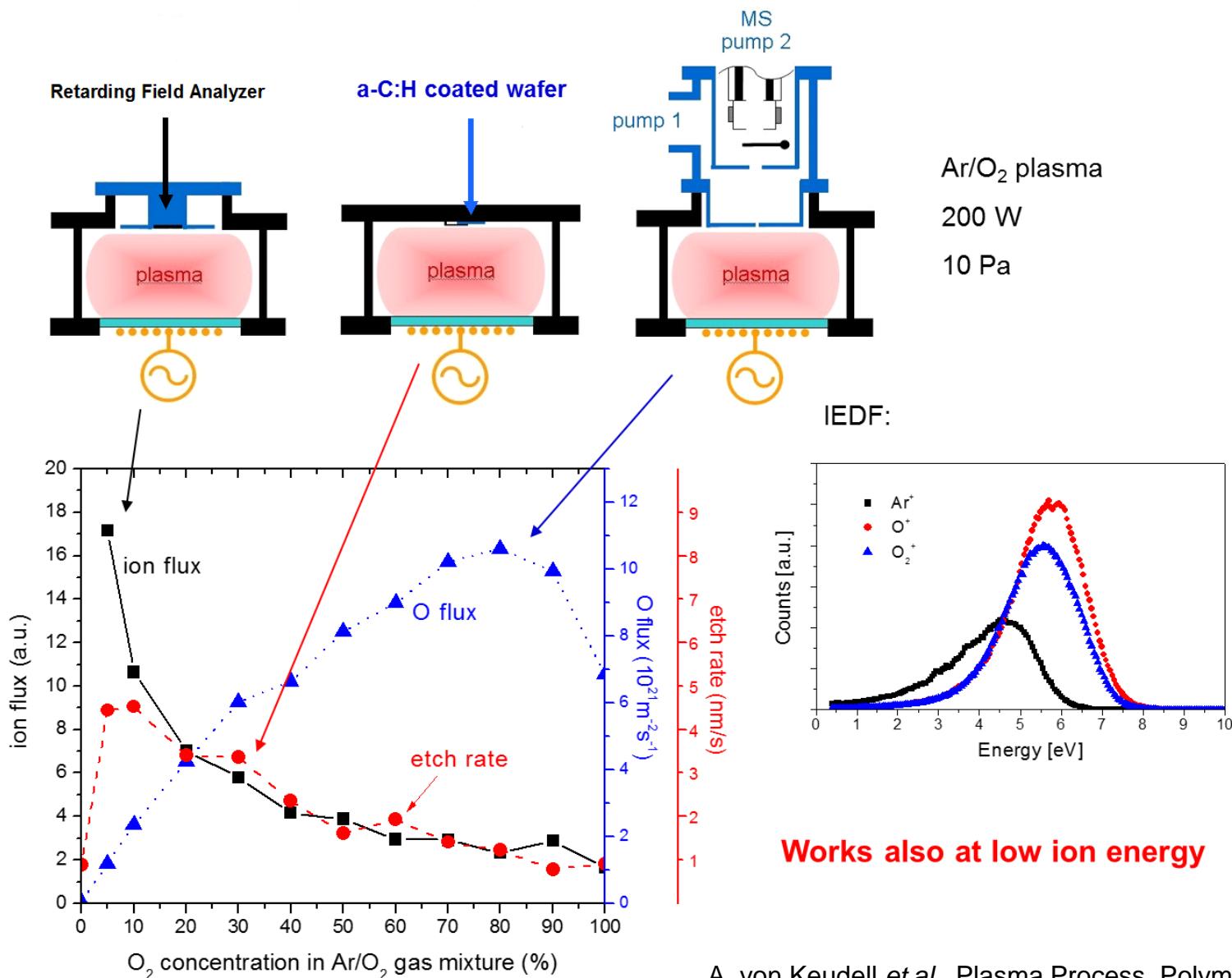


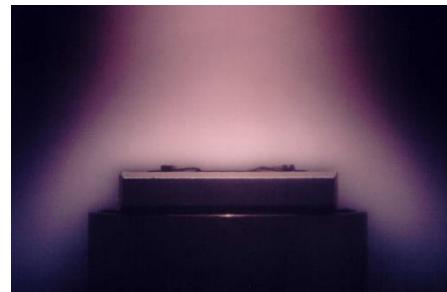
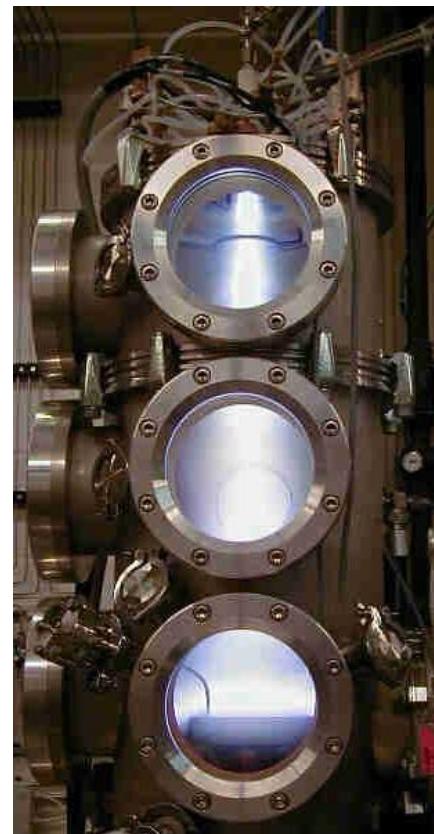
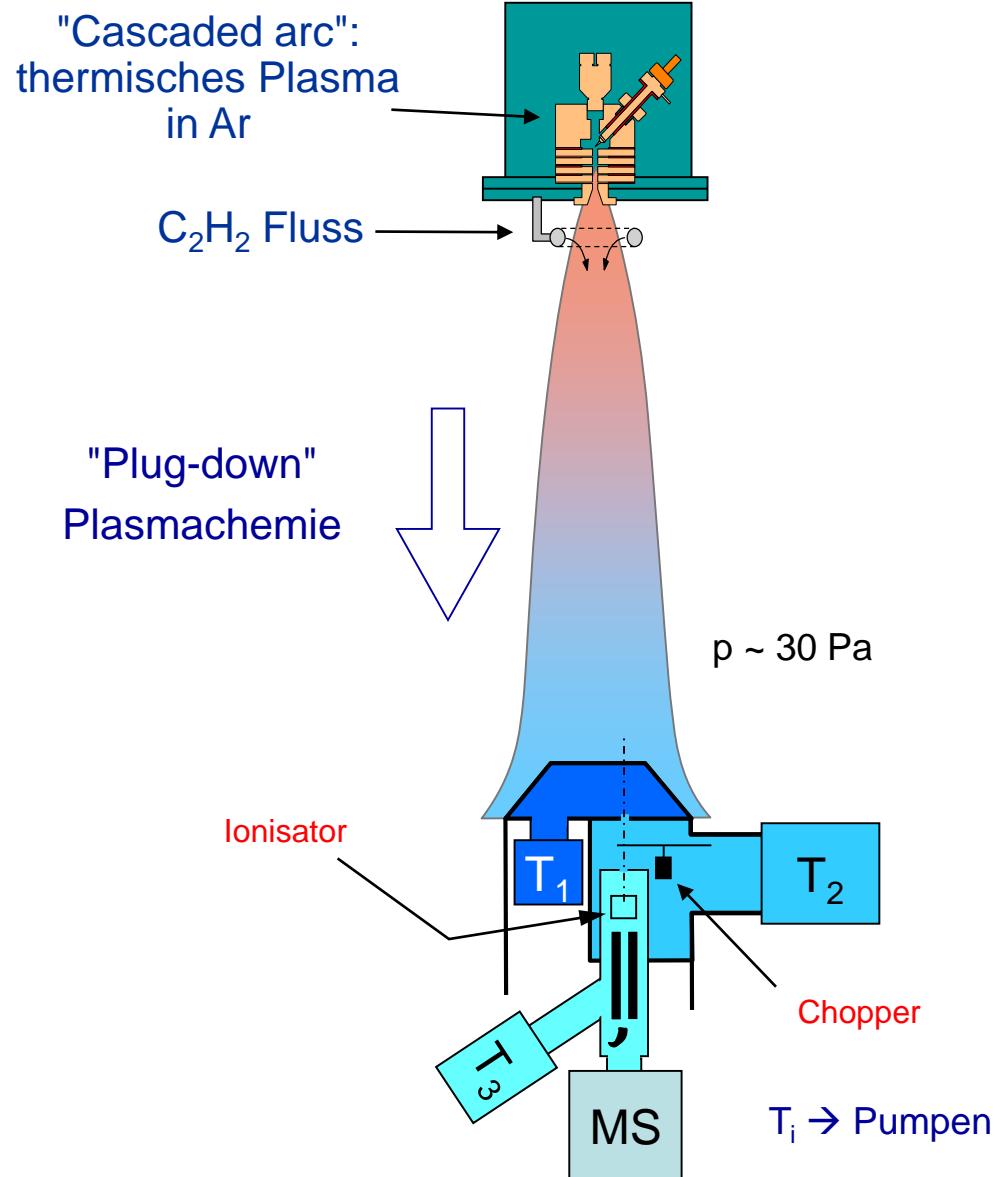
Abbildung 3.1: Skizze des Versuchsaufbaus. (entnommen aus [10])



Example: a-C:H etching mechanism in Ar/O₂ ICP



Example: MS of radicals in C_2H_2 plasma



Example: reaction path in Ar/C₂H₂ plasma TU/e



im interstellaren
Raum



bei der Verbrennung



Neu:

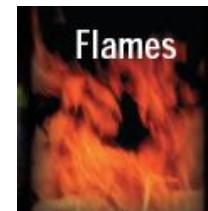
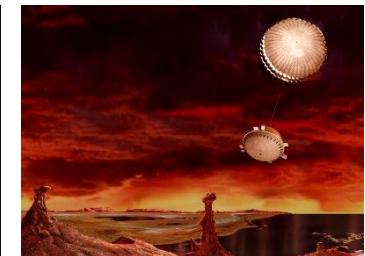
bei der Abscheidung
von a-C:H Schichten



in Fusionsreaktoren

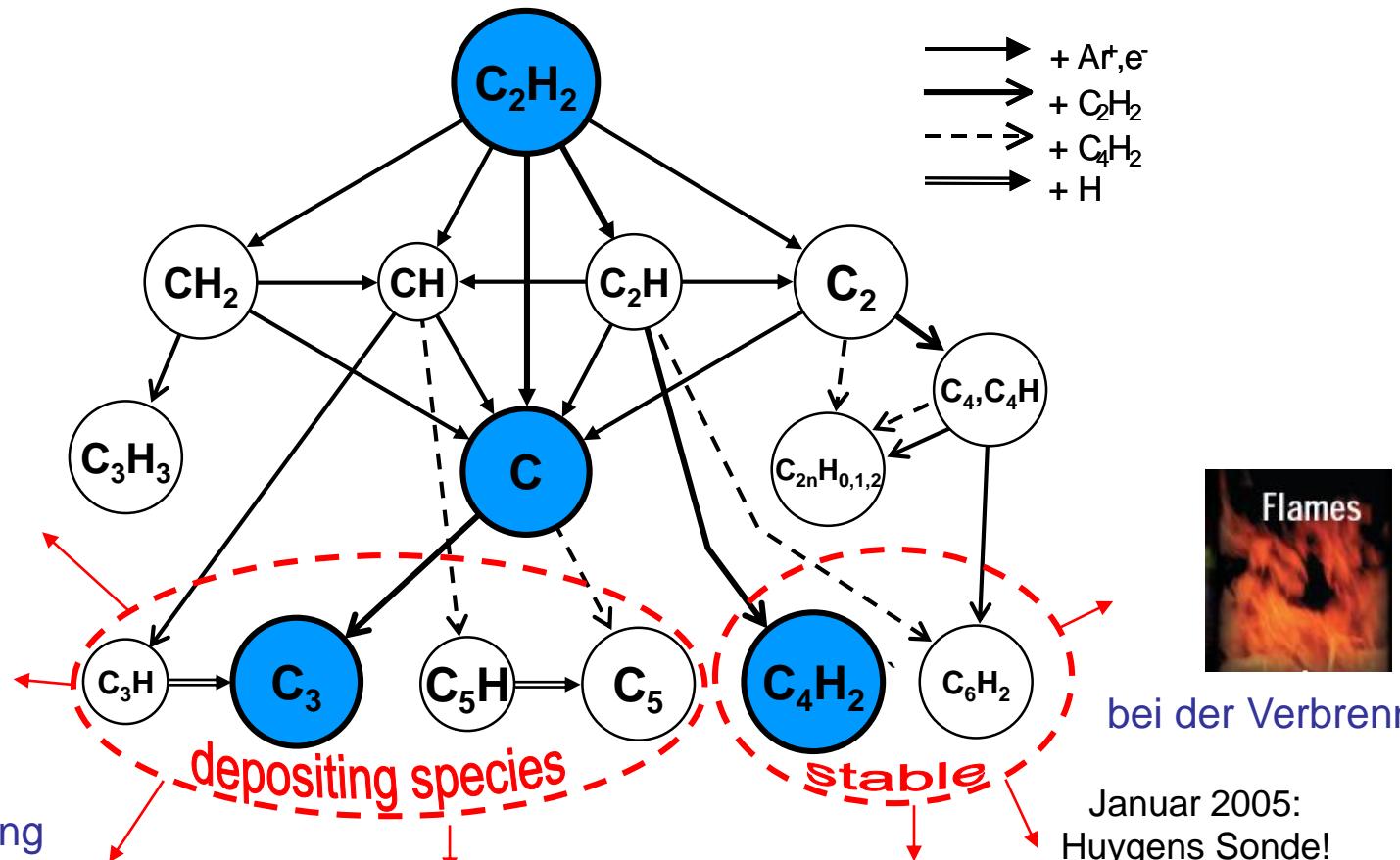


auf dem Saturn-Mond Titan



bei der Verbrennung

Januar 2005:
Huygens Sonde!



Example: Ion energy distribution functions in rf-plasma

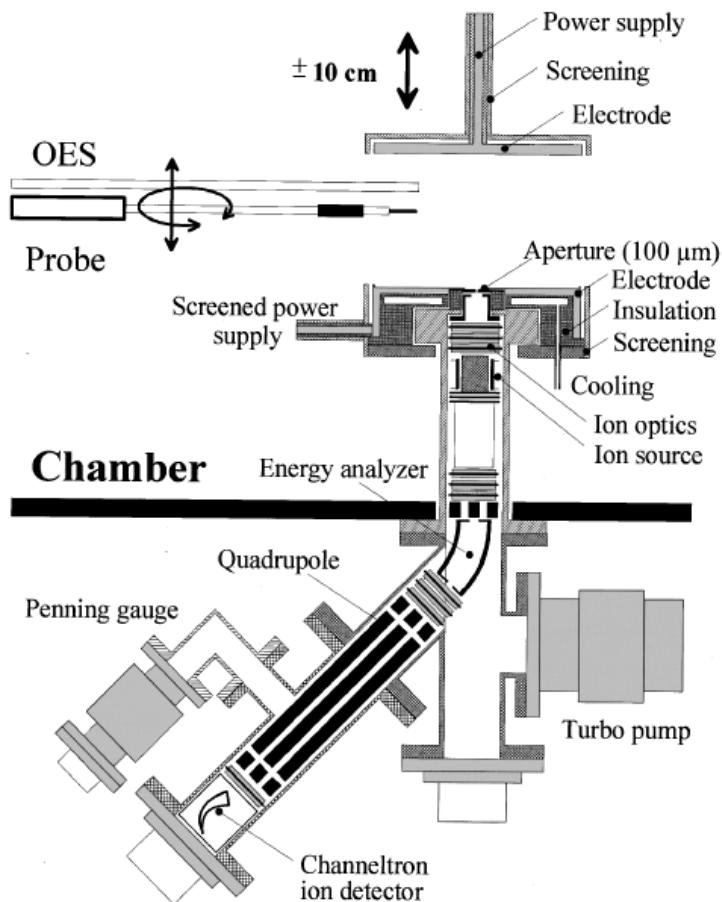
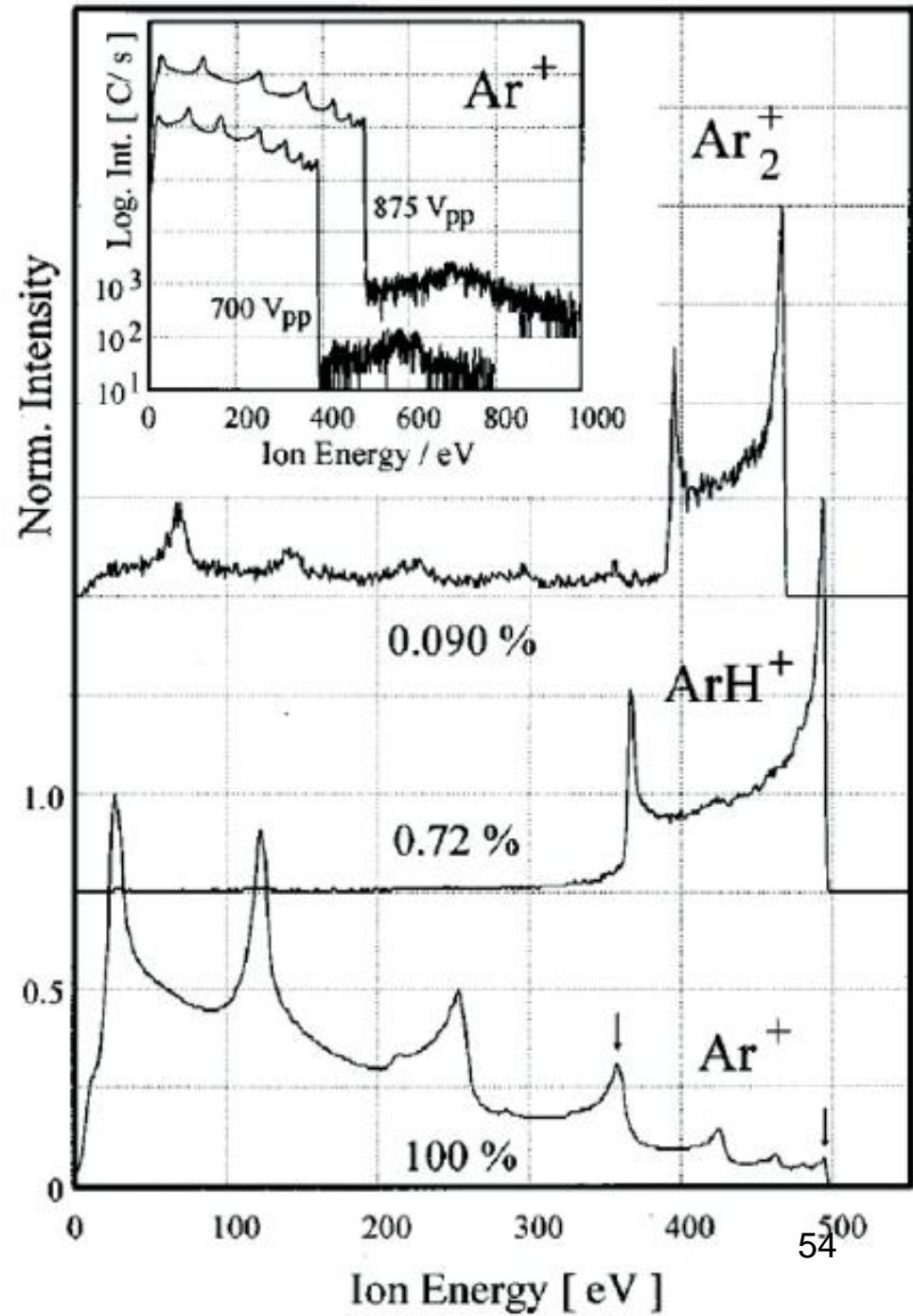


FIG. 1. Schematic diagram of the discharge arrangement.

[92] Zeuner M, Neumann H and Meichsner J
1997 J. Appl. Phys. 81 2985



Example: Ion energy distribution functions in HiPIMS plasmas

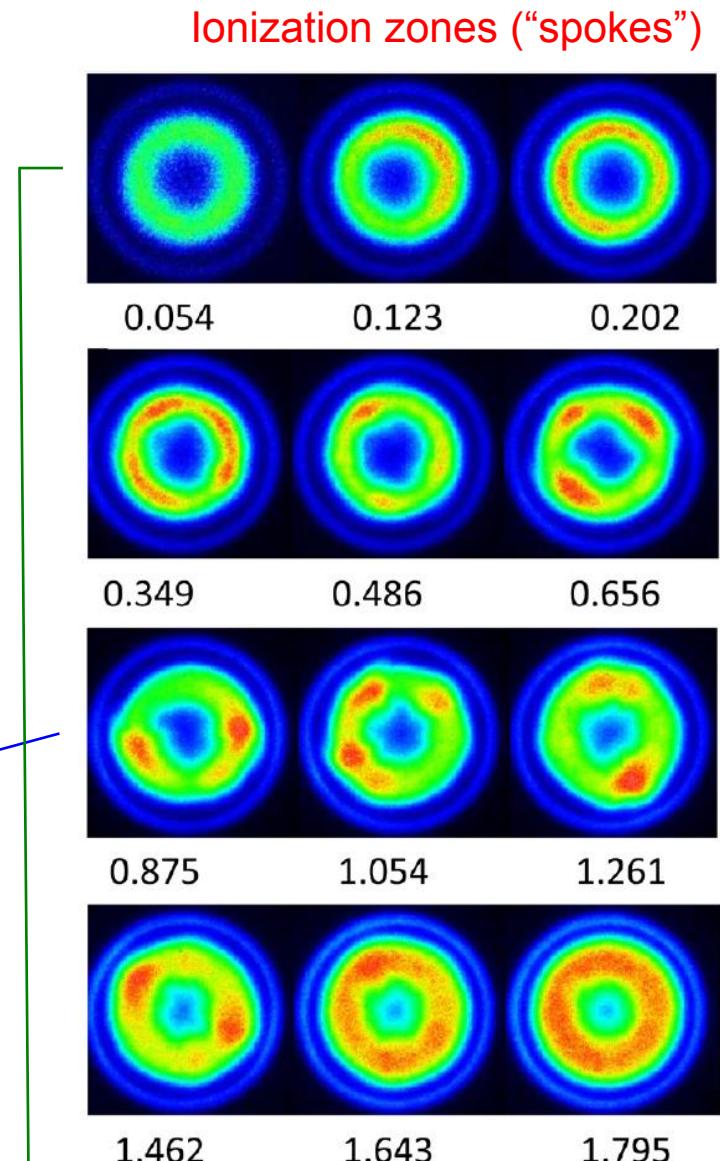
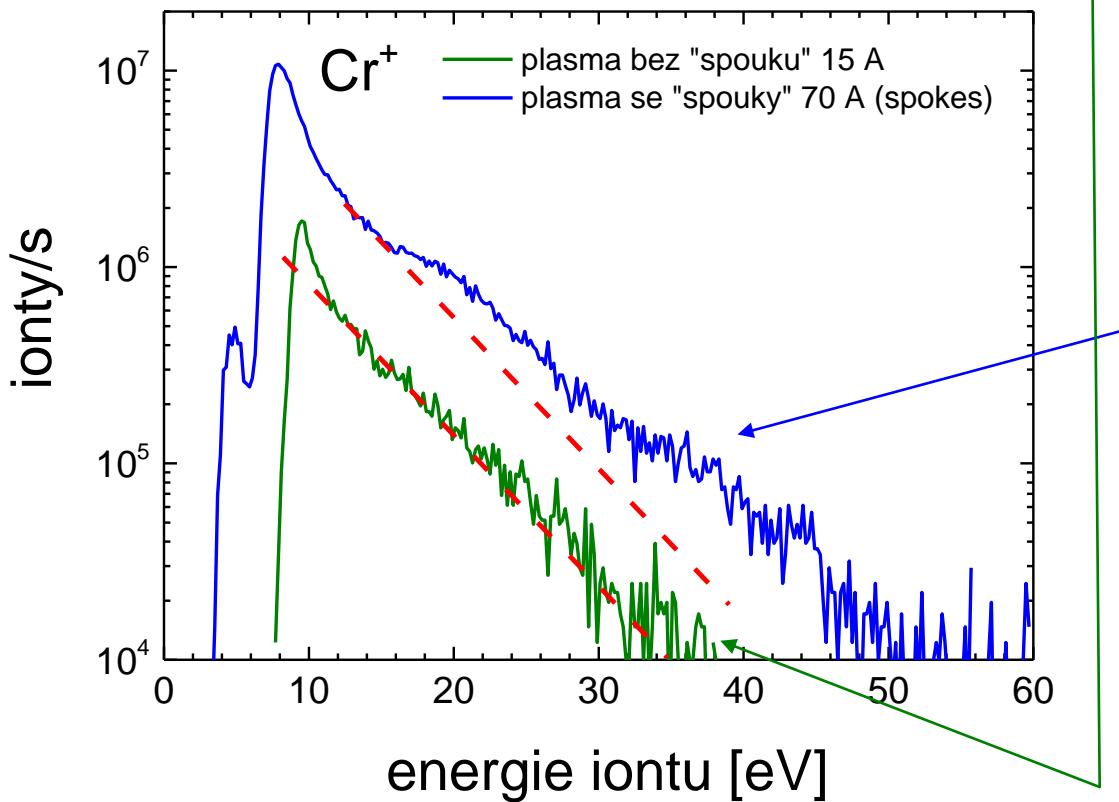


Figure 2. ICCD images of a chromium target at different power densities in kW cm^{-2} as indicated. The images are taken at $180 \mu\text{s}$ of $200 \mu\text{s}$ pulses and Ar at 0.26 Pa .

Conclusions

MS is a powerful diagnostic for plasma analysis:

- Detects the relative fluxes of positive and negative ions including the information about their energies
- Provides absolute densities of neutral stable and reactive species
- Careful design of MS diagnostic setup important (is not trivial)
- Can be successfully applied to analysis of atmospheric pressure plasmas